


ESE3700: Circuit-Level Modeling, Design and Optimization for Digital Systems

Lec 5: February 7, 2024

MOS Model and Transistor Operating Regions, Part I





You are Here: Transistor Edition

- ❑ Previously: simple models (0th and 1st order)
 - Comfortable with basic functions and circuits
- ❑ This lecture and the next one
 - Detailed semiconductor discussion
 - MOSFET phenomenology
- ❑ Rest of term
 - Implications of the MOS device



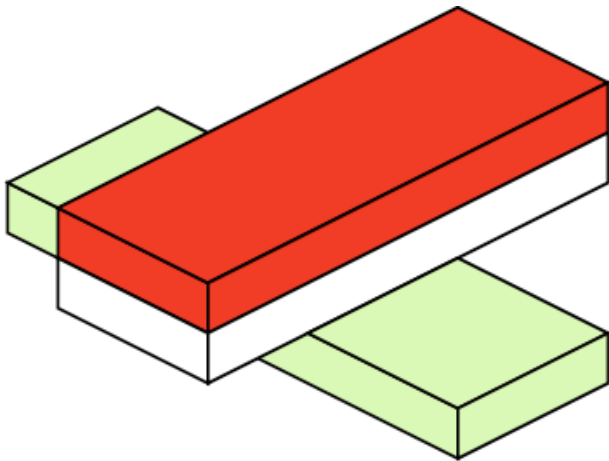
Today

- ❑ MOS Structure
- ❑ Basic Fabrication
- ❑ Threshold
- ❑ Operating Regions
 - Resistive
 - Saturation
 - Subthreshold
 - Velocity Saturation (next lecture)

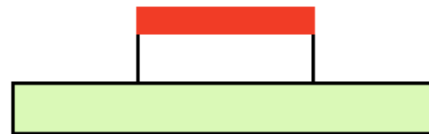


MOS

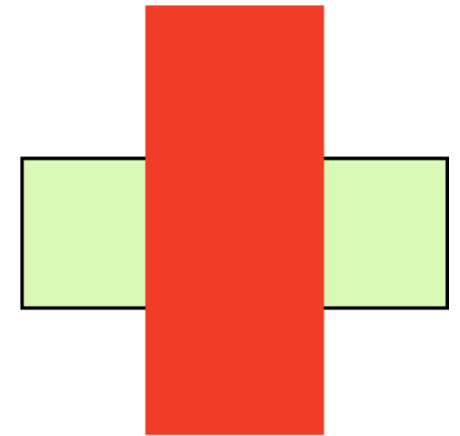
□ Metal Oxide Semiconductor



Oblique



Side

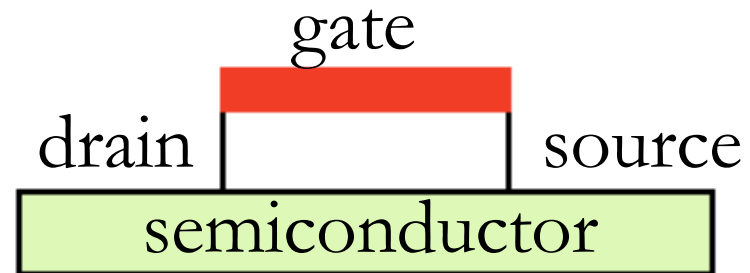
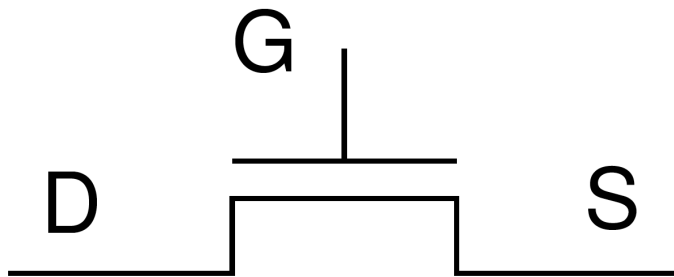


Top



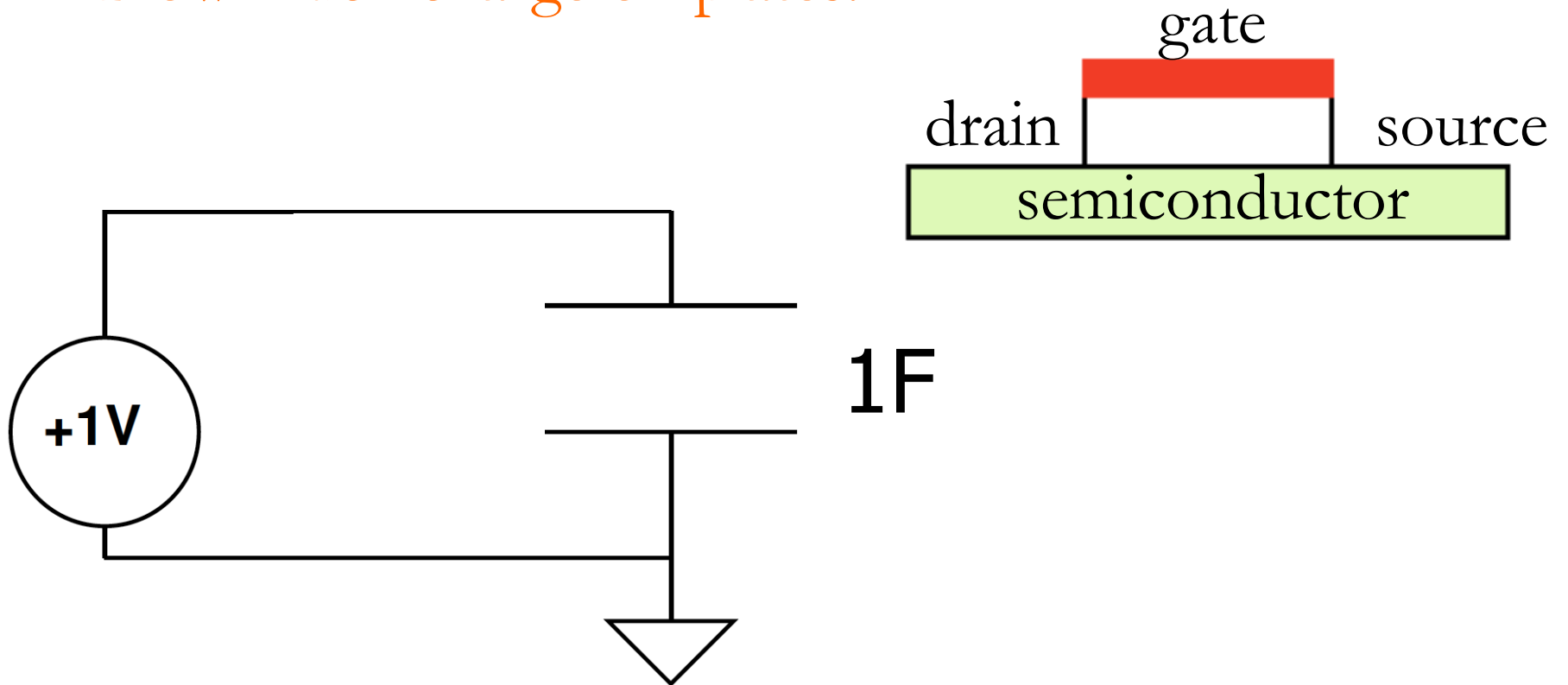
MOS

- ❑ **M**etal – gate
- ❑ **O**xide – insulator separating gate from semiconductor
 - Ideally: no conduction from gate to semiconductor
- ❑ **S**emiconductor – between source and drain
- ❑ See why gate input is capacitive?



(MOS) Capacitor (preclass 1)

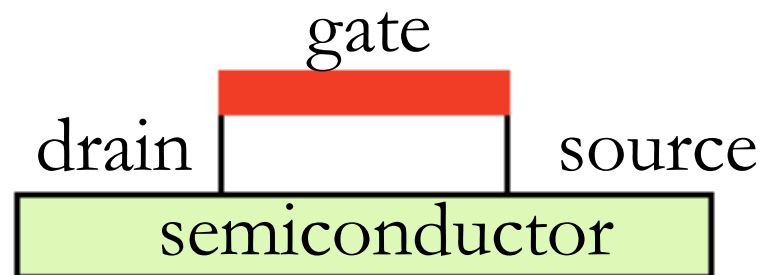
- Charge distribution and field?
- How much charge on plates?





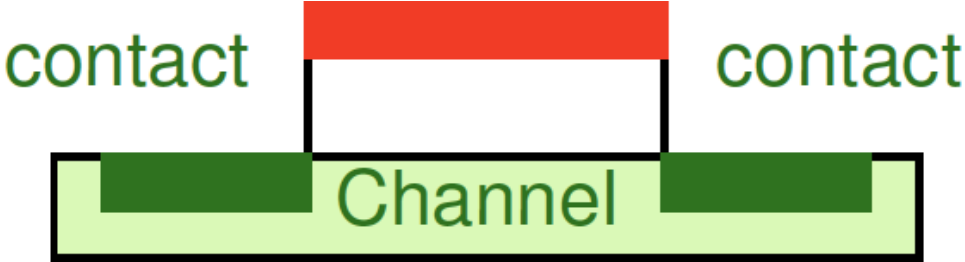
Idea

- ❑ Semiconductor – can behave as metal or insulator
- ❑ Voltage on gate induces an electrical field
- ❑ Induced field attracts (repels) charge in semiconductor to form a channel
 - Semiconductor can be switched between conducting and not conducting
 - Hence “Field-Effect” Transistor





Source/Drain Contacts



- Contacts: Conductors → metallic
 - Connect to metal wires that connect transistors



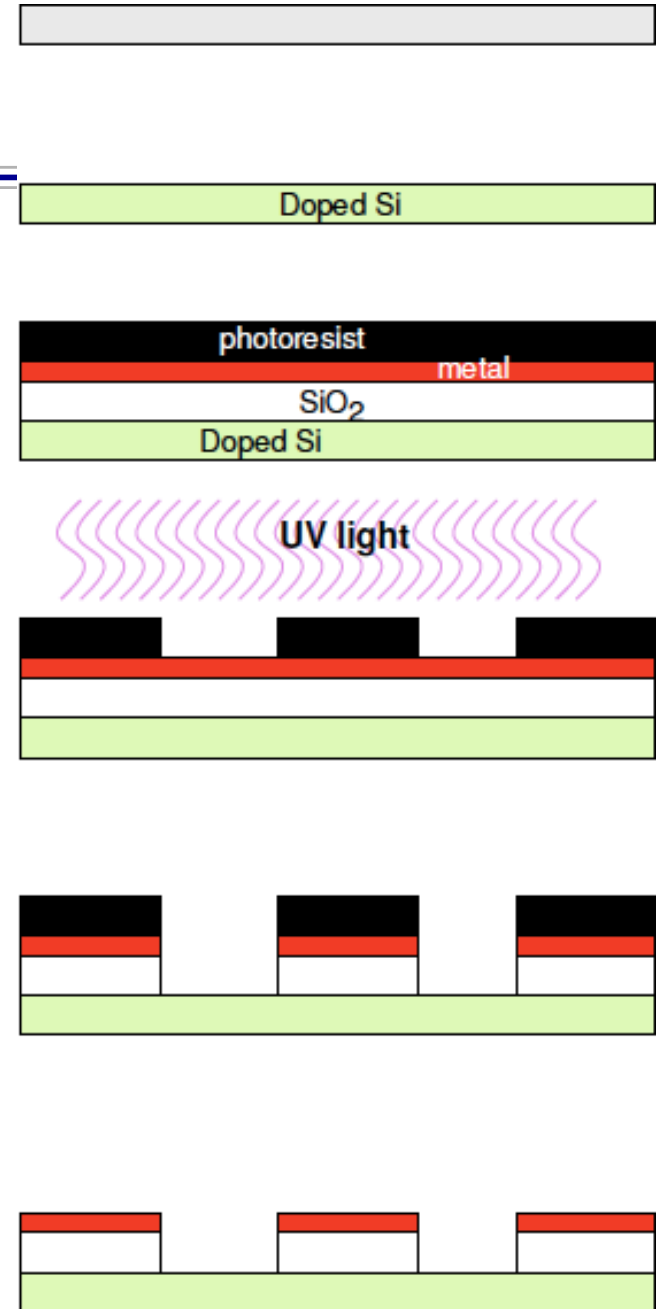


Fabrication

- ❑ Start with Silicon wafer
- ❑ Dope silicon
- ❑ Grow Oxide (SiO_2)
- ❑ Deposit Metal
- ❑ Photoresist mask and etch to define where features go

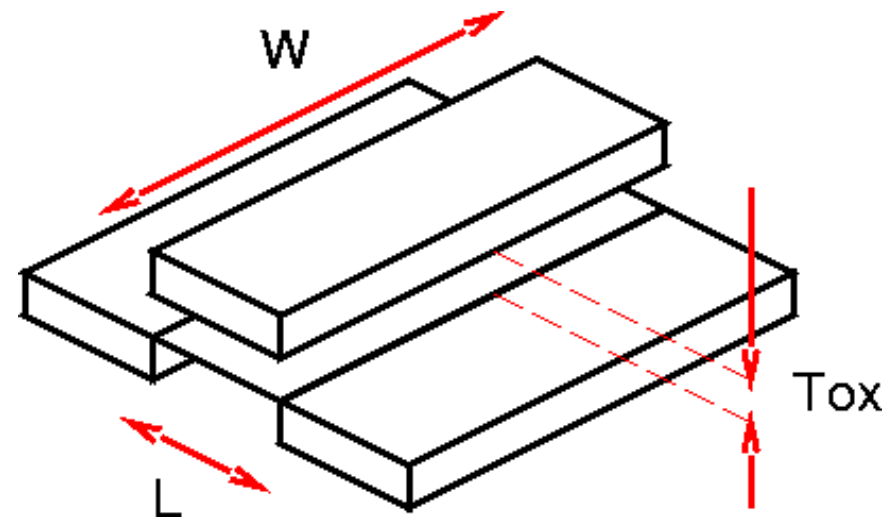
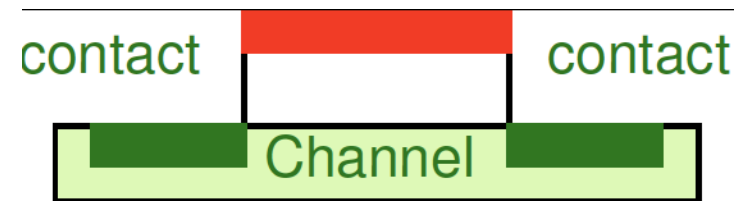
<https://youtu.be/35jWSQXku74?t=119>

Time Code: 2:00-4:30



Dimensions

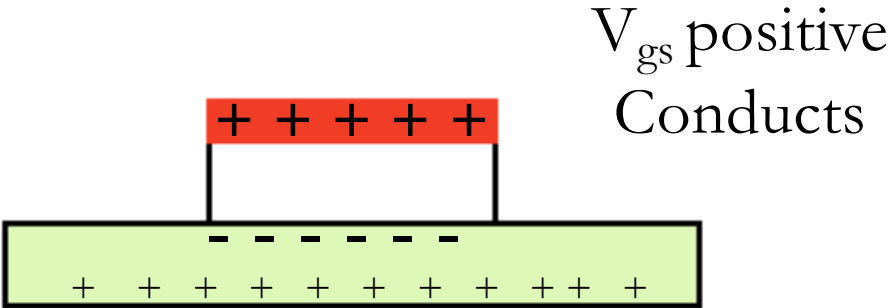
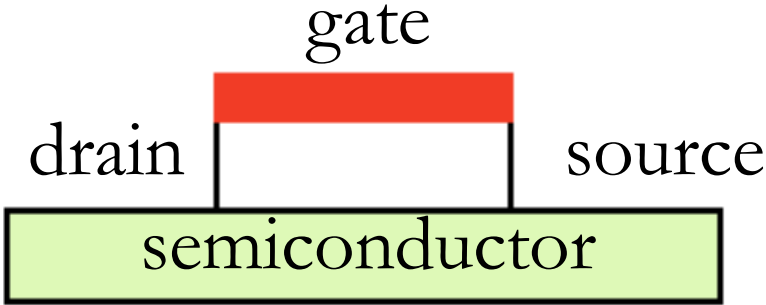
- ❑ Channel Length (L)
 - ❑ Channel Width (W)
 - ❑ Oxide Thickness (T_{ox})
-
- ❑ Process named by minimum length
 - $22\text{nm} \rightarrow L=22\text{nm}$



MOS Transistor Operation



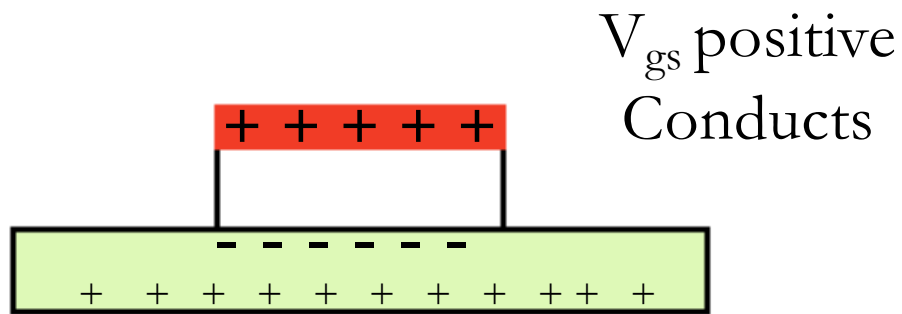
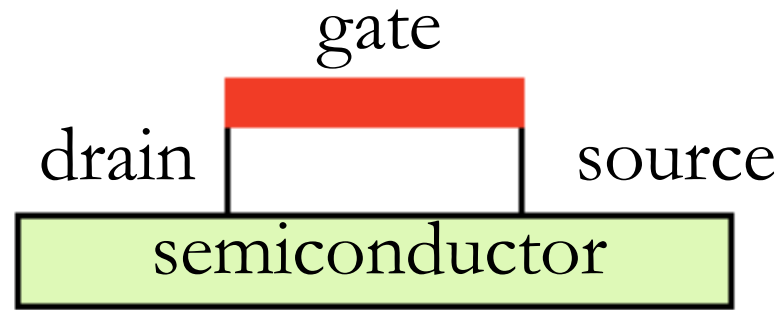
So far– MOS model



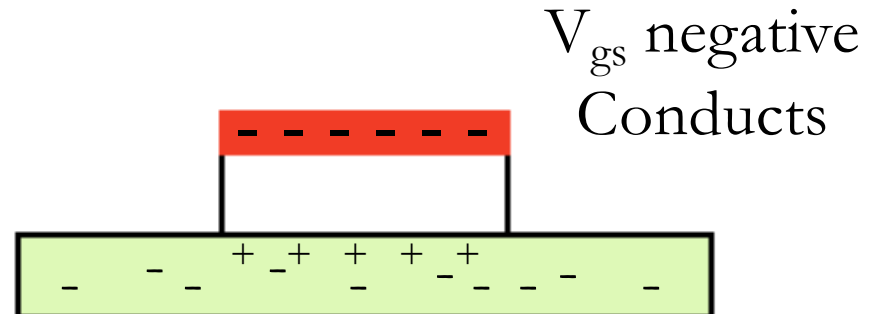
NMOS



So far– MOS model



NMOS

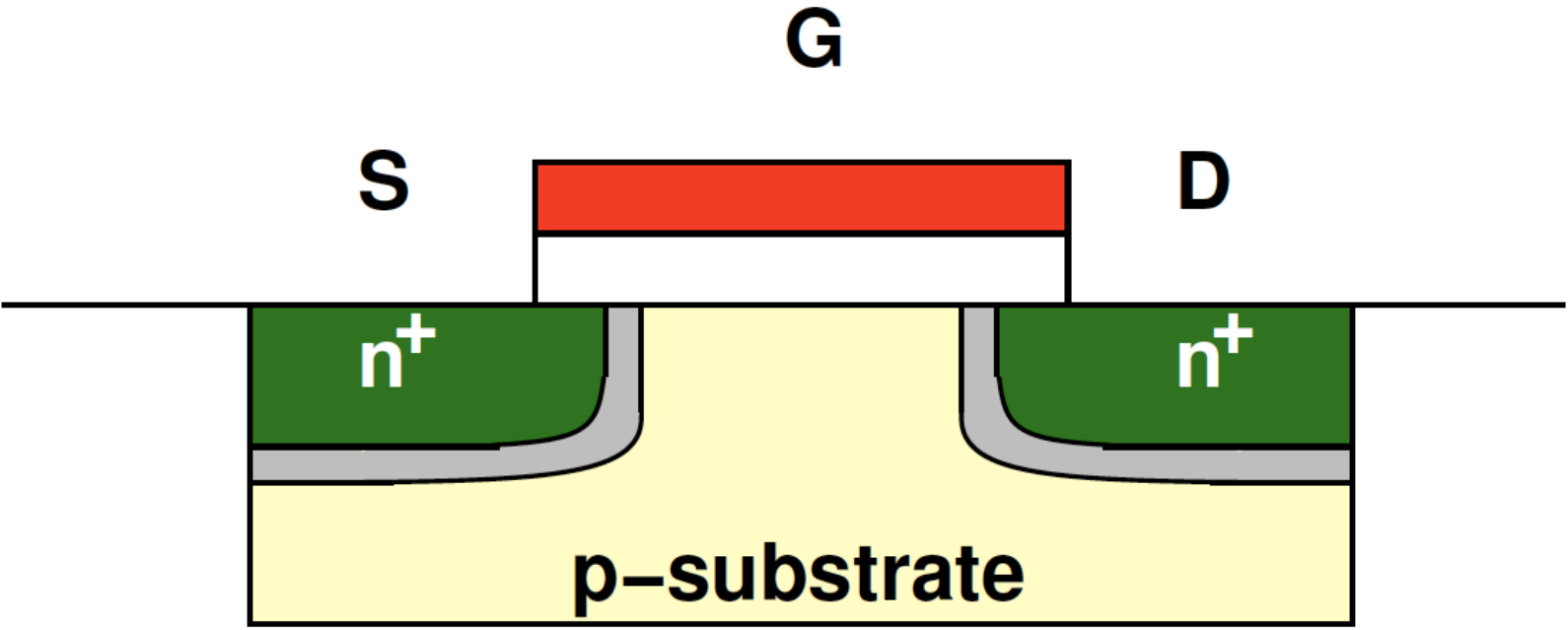


PMOS



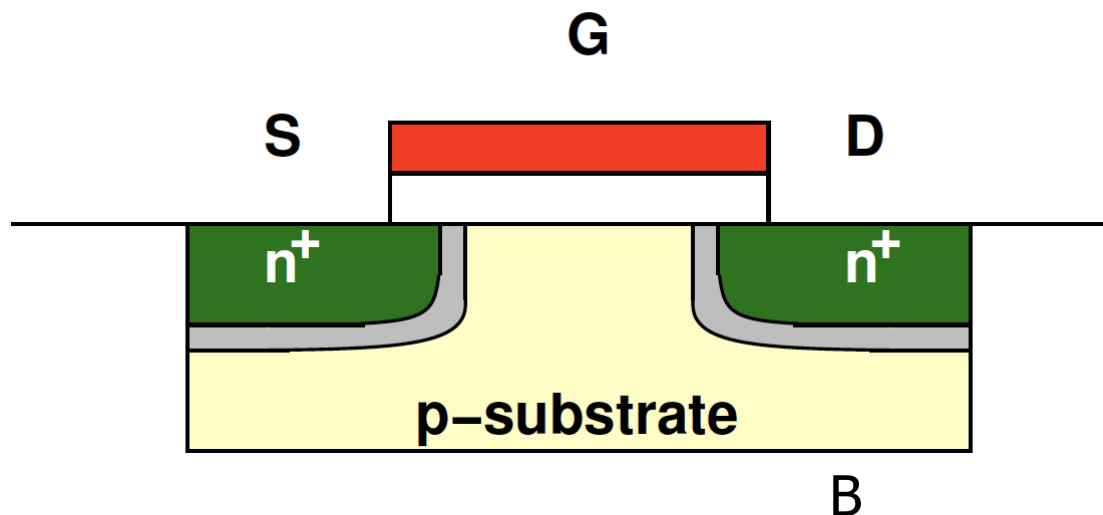
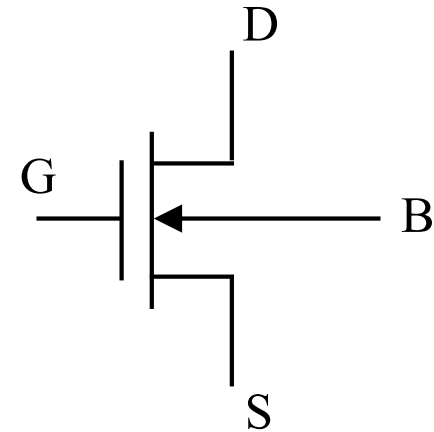
Refinement

- Depletion region around D/S \rightarrow excess carriers depleted



Bulk/Body Contact

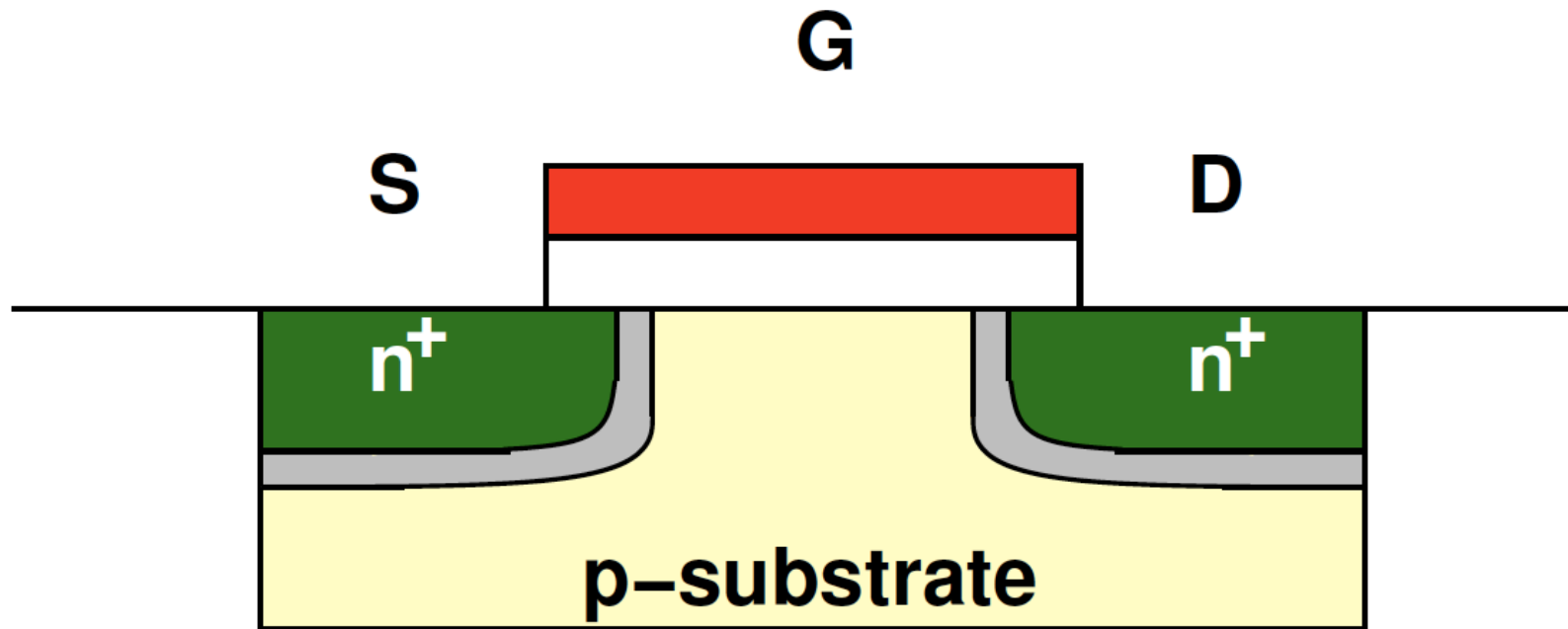
- ❑ MOS actually has four contacts
- ❑ Also effects fields
- ❑ Ideally substrate and source connected
 - Settle for substrate being \leq source
 - Gnd for nmos (V_{dd} for pmos)





No Field

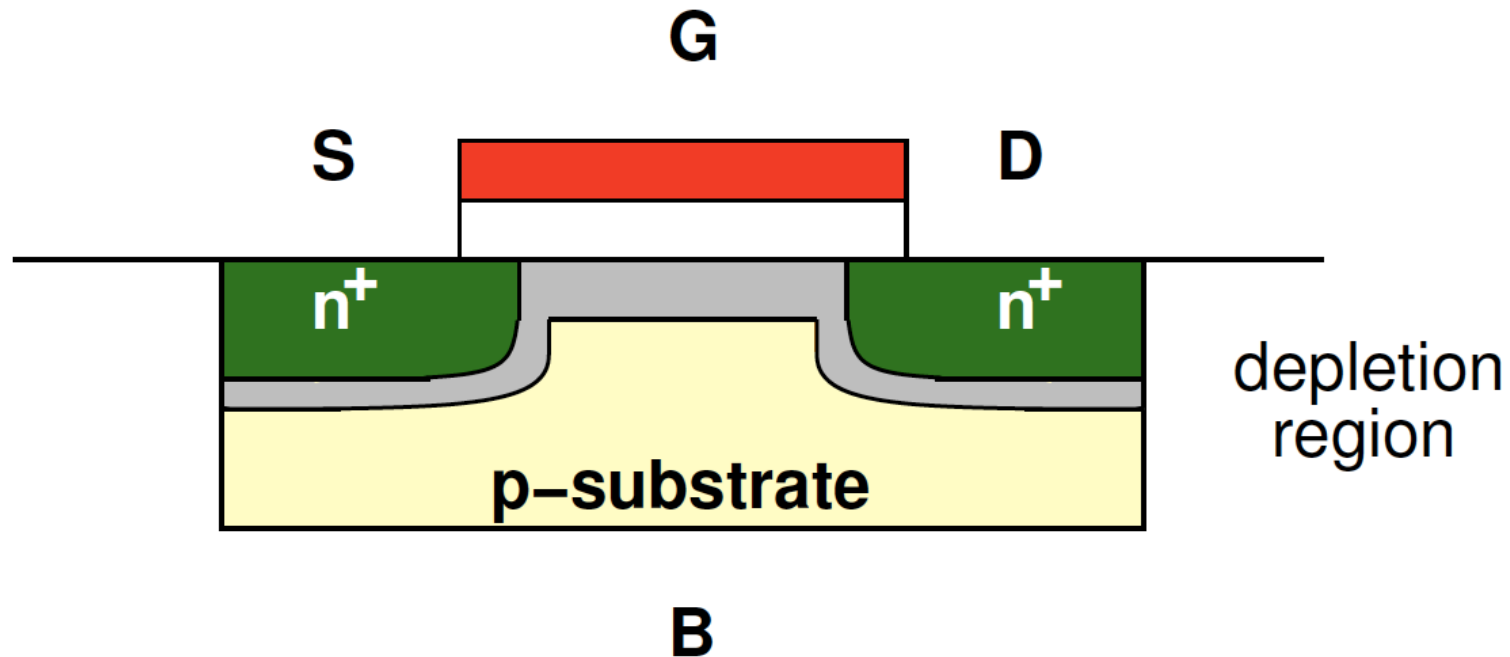
- $V_{GS}=0, V_{DS}=0$



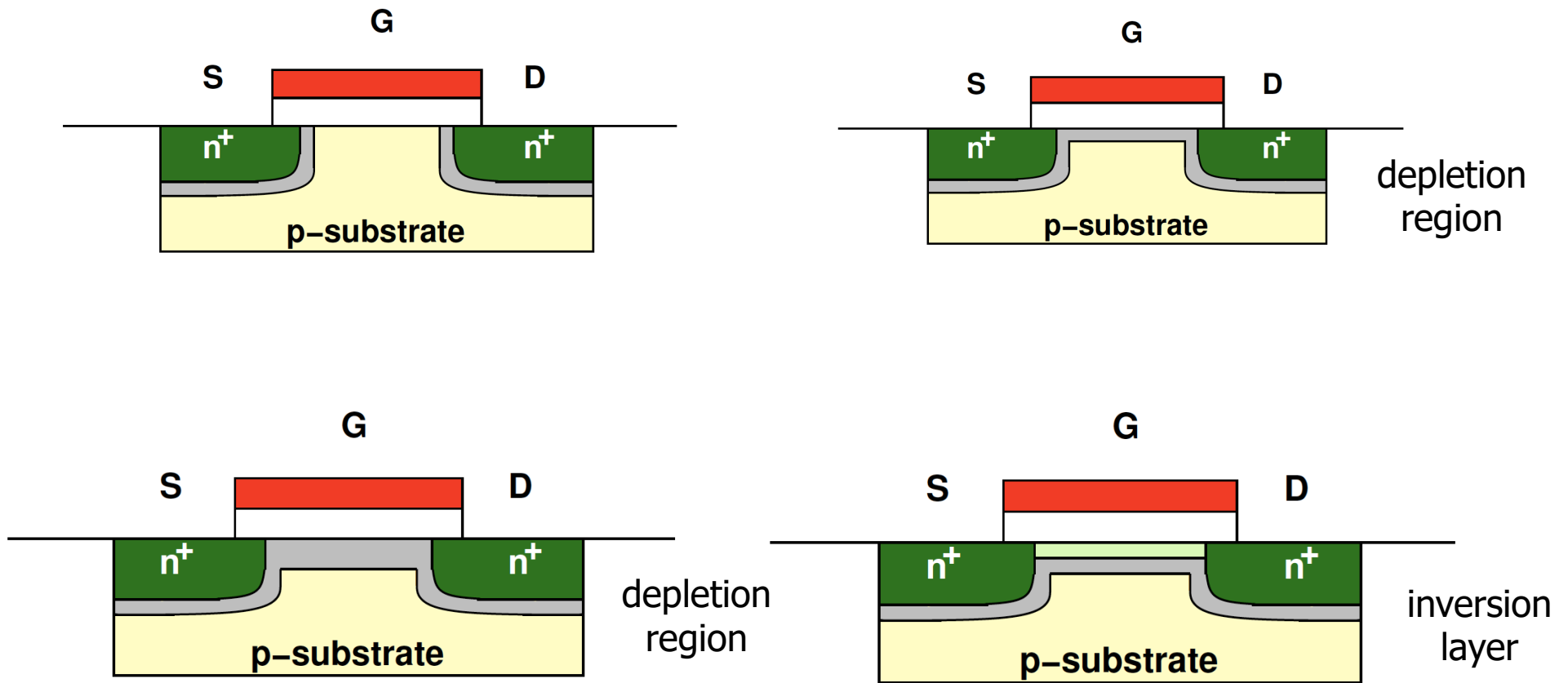


Apply $V_{GS} > 0$

- ❑ Deplete excess positive charge under oxide
- ❑ Left with negative charge
 - Repel holes



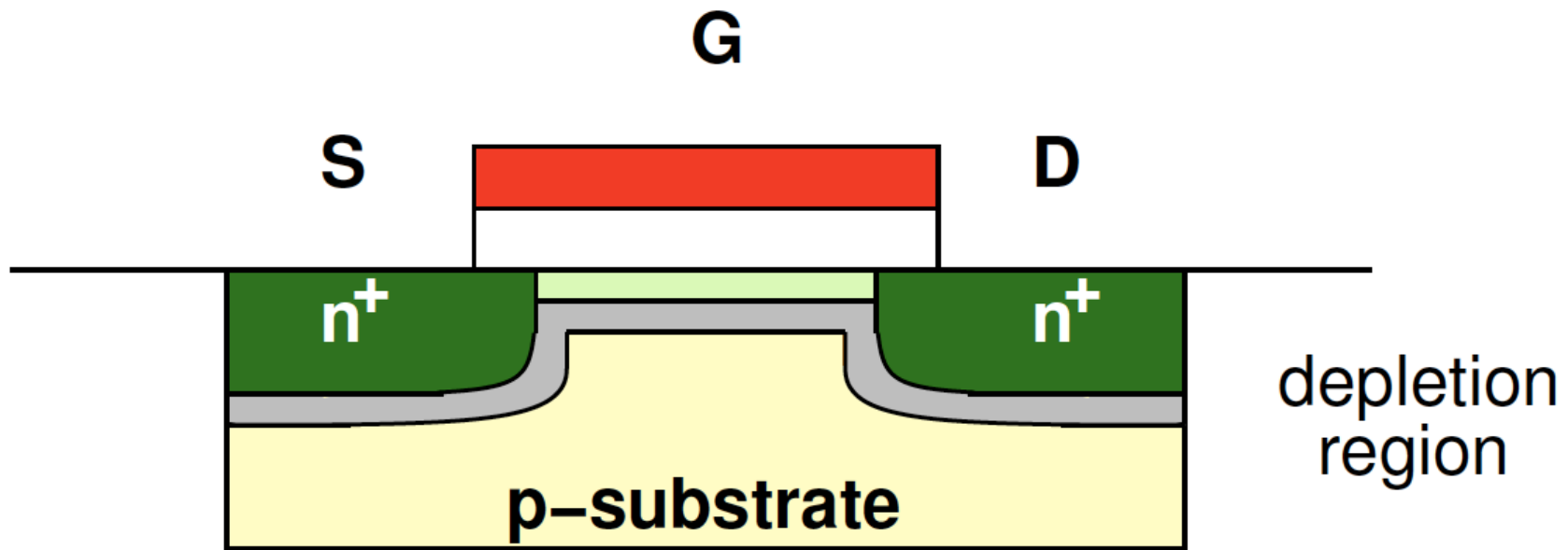
Channel Evolution -- Increasing V_{gs}





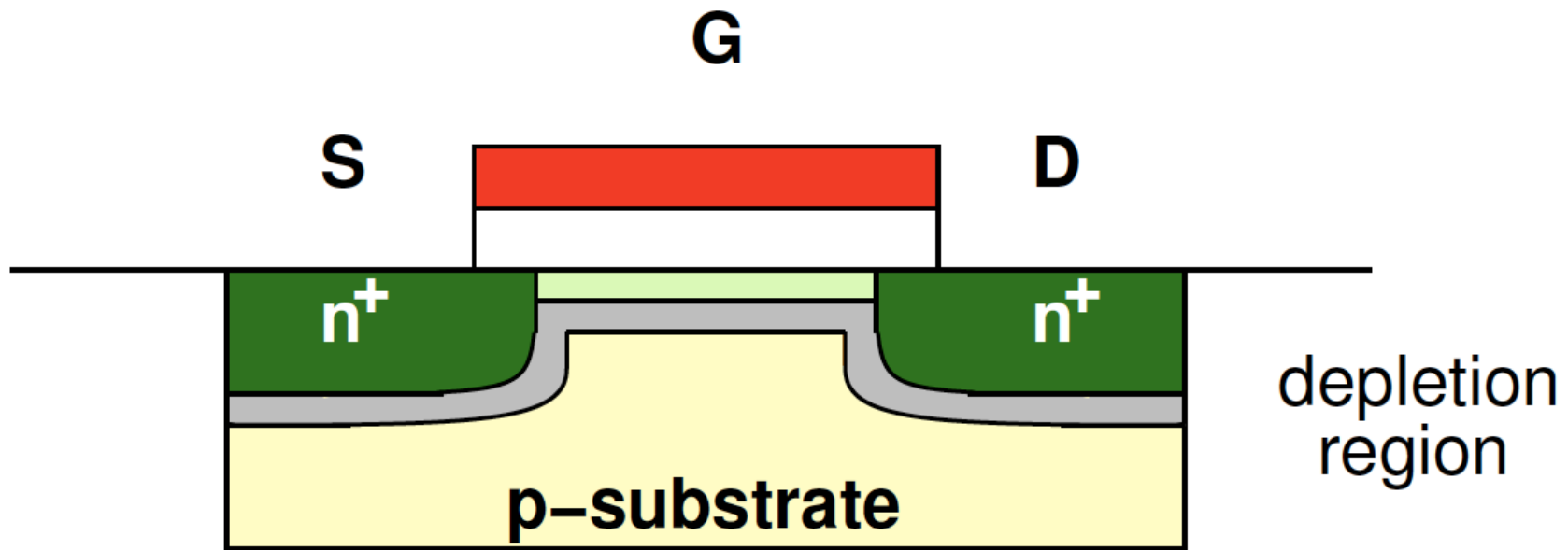
Inversion

- ❑ Surface builds electrons
 - Inverts to n-type
 - Draws electrons from n^+ source terminal



Threshold

- Voltage where strong inversion occurs → threshold voltage
 - $V_{th} \approx 2\phi_F$

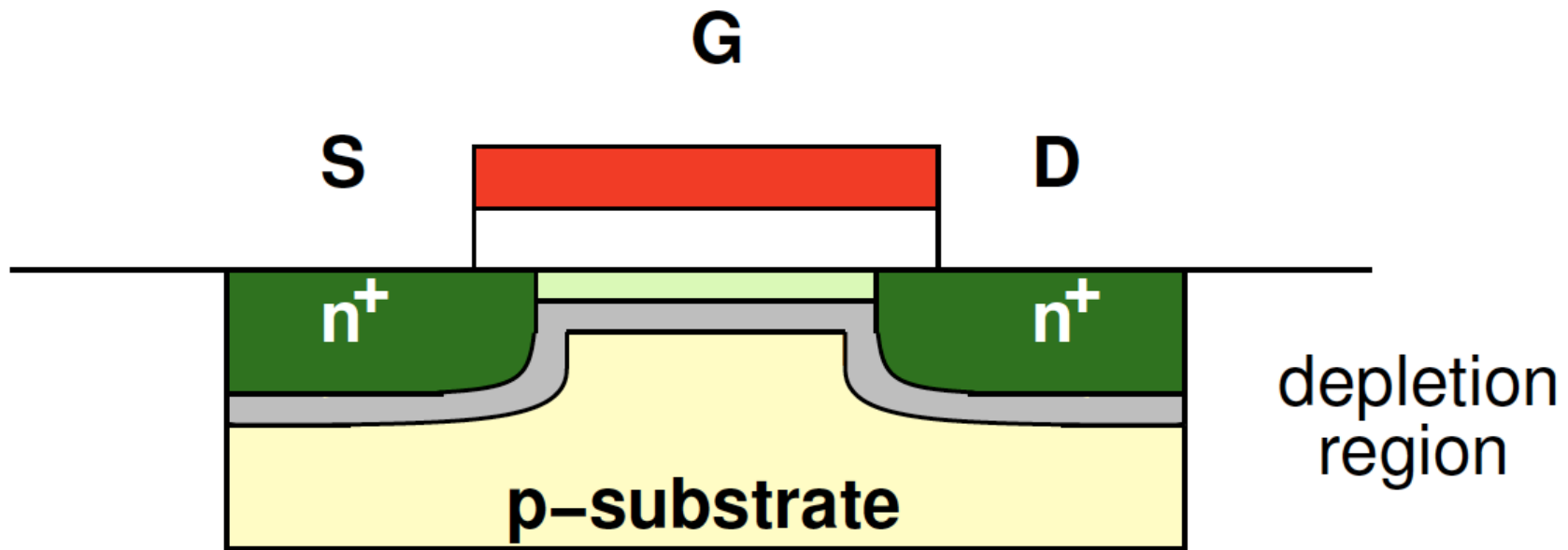


Threshold

- Voltage where strong inversion occurs \rightarrow threshold voltage

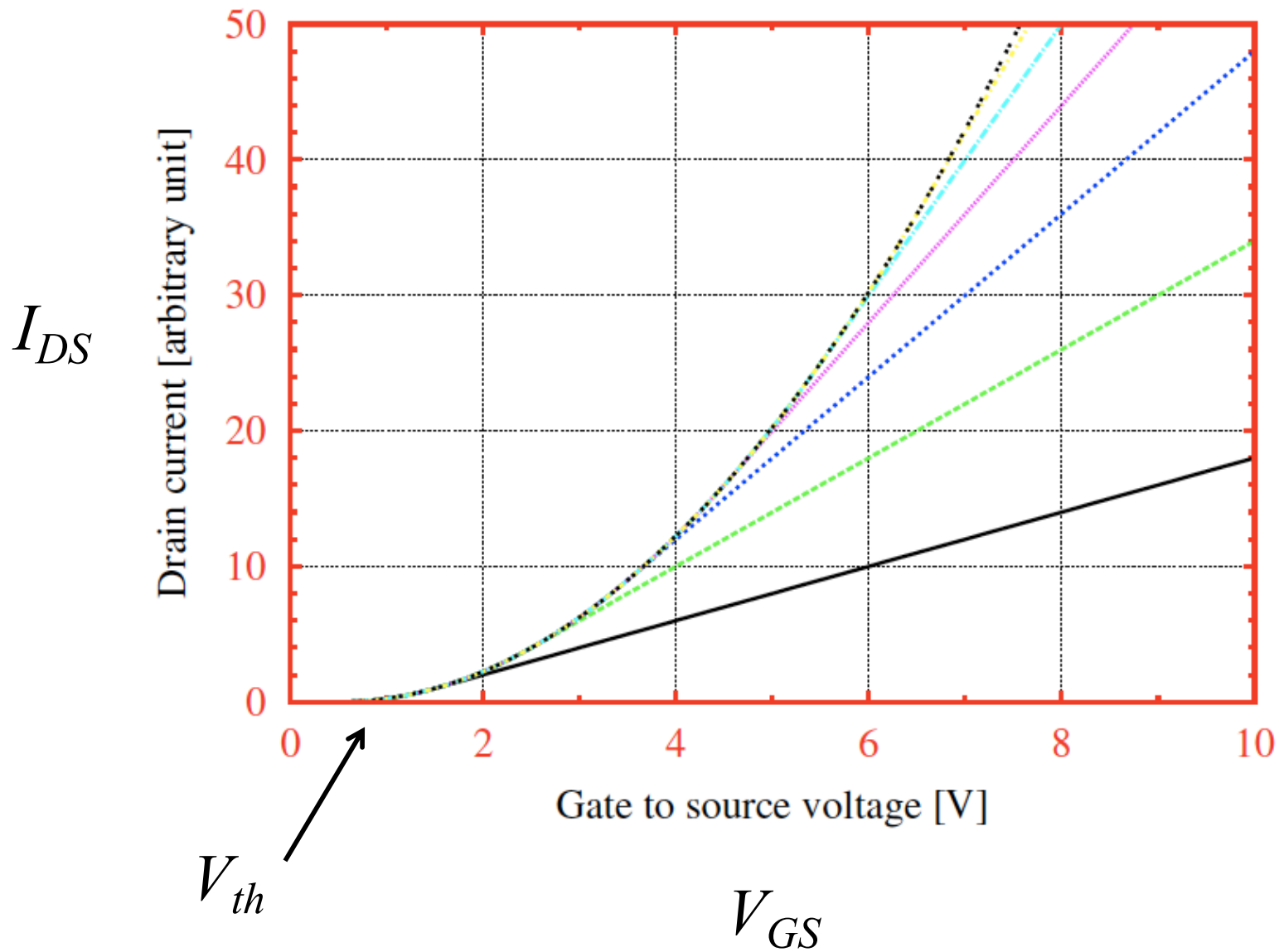
- $V_{th} \approx 2\phi_F$

- Engineer by controlling doping (N_A) $\phi_F = \frac{kT}{q} \ln\left(\frac{N_A}{n_i}\right)$



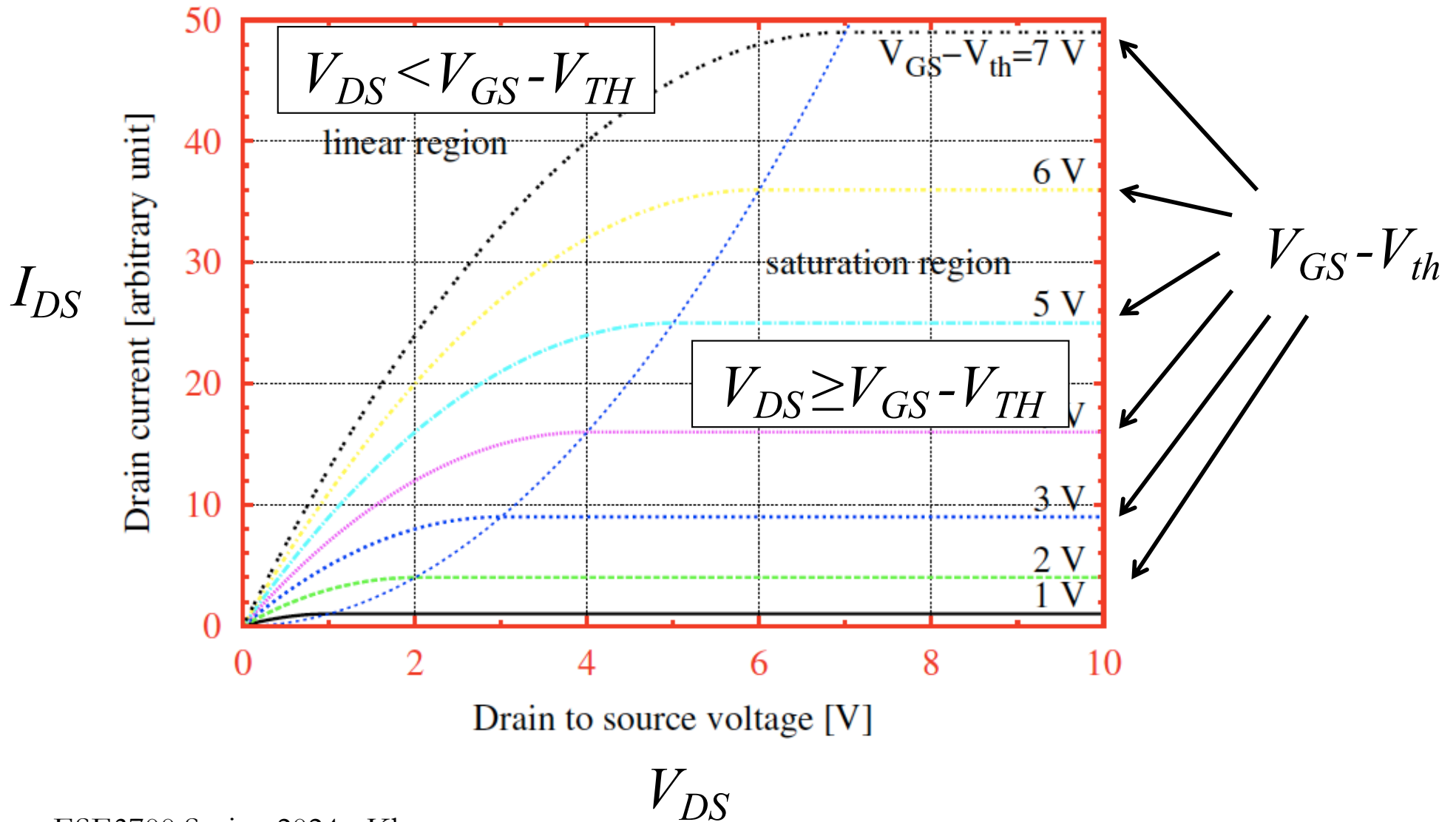


MOSFET – IV Characteristics



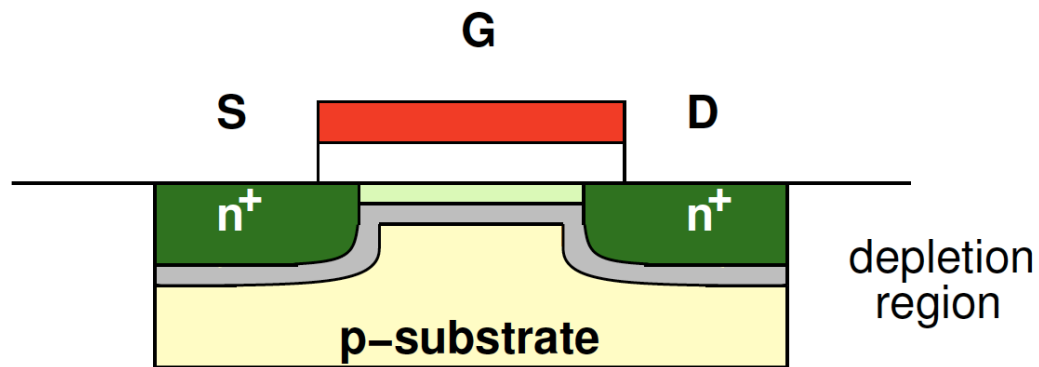


MOSFET – IV Characteristics



Linear Region

- $V_{GS} > V_{th}$ and V_{DS} small



$$C_{OX} = \frac{\epsilon_{OX}}{t_{OX}}$$

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$



Linear Region

- $V_{GS} > V_{th}$ and V_{DS} small
- V_{GS} fixed \rightarrow looks like resistor
 - Current linear in V_{DS}

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$



Linear Region

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- V_{GS} fixed \rightarrow looks like resistor
 - Current linear in V_{DS}

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

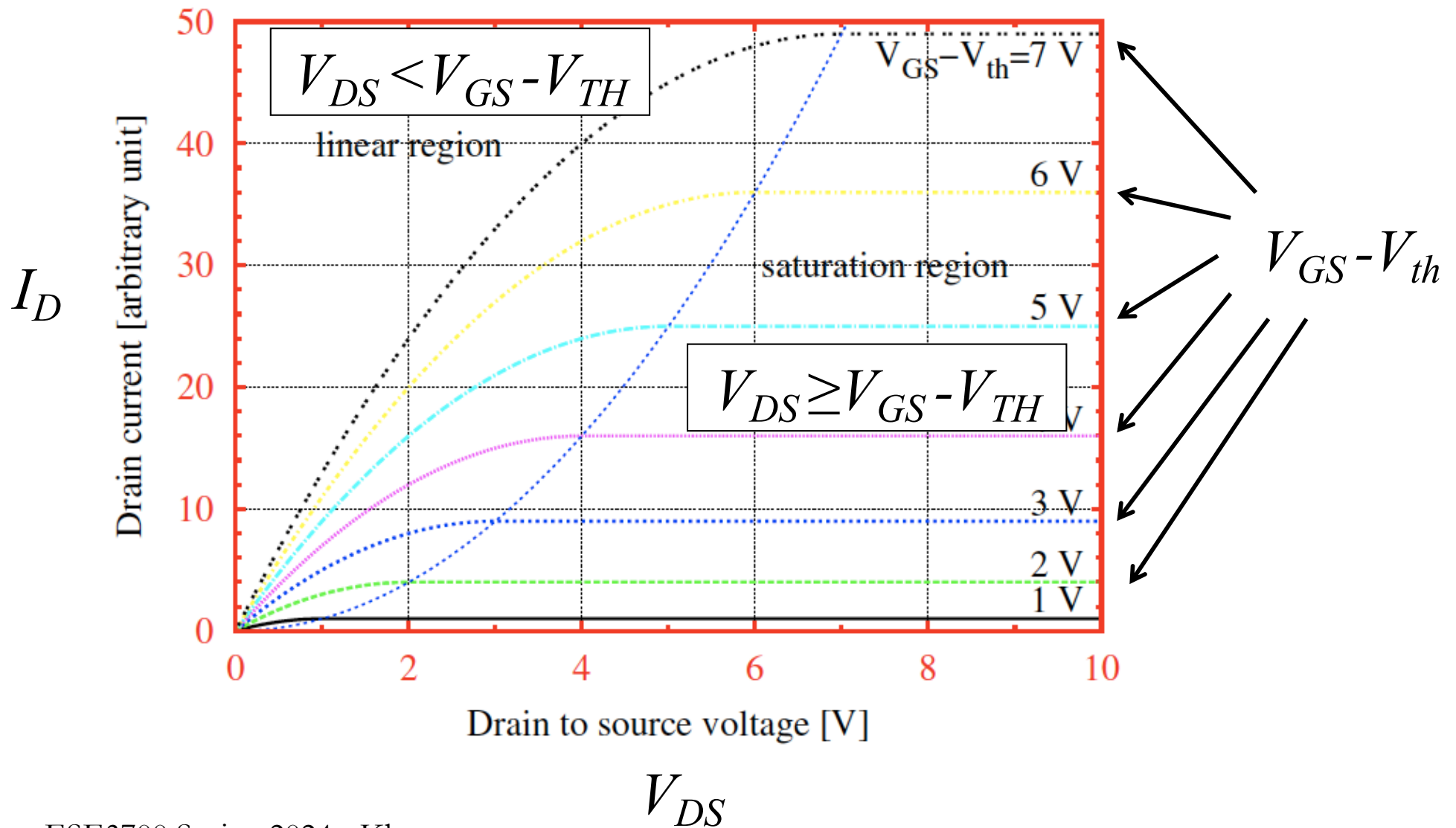
A blue arrow points from the $\frac{V_{DS}^2}{2}$ term to a blue ~ 0 symbol, indicating that this term is negligible in the linear region.

$$I_{DS} \approx \mu_n C_{OX} \left(\frac{W}{L} \right) (V_{GS} - V_{th}) V_{DS}$$

$$I_{DS} \propto V_{DS}$$



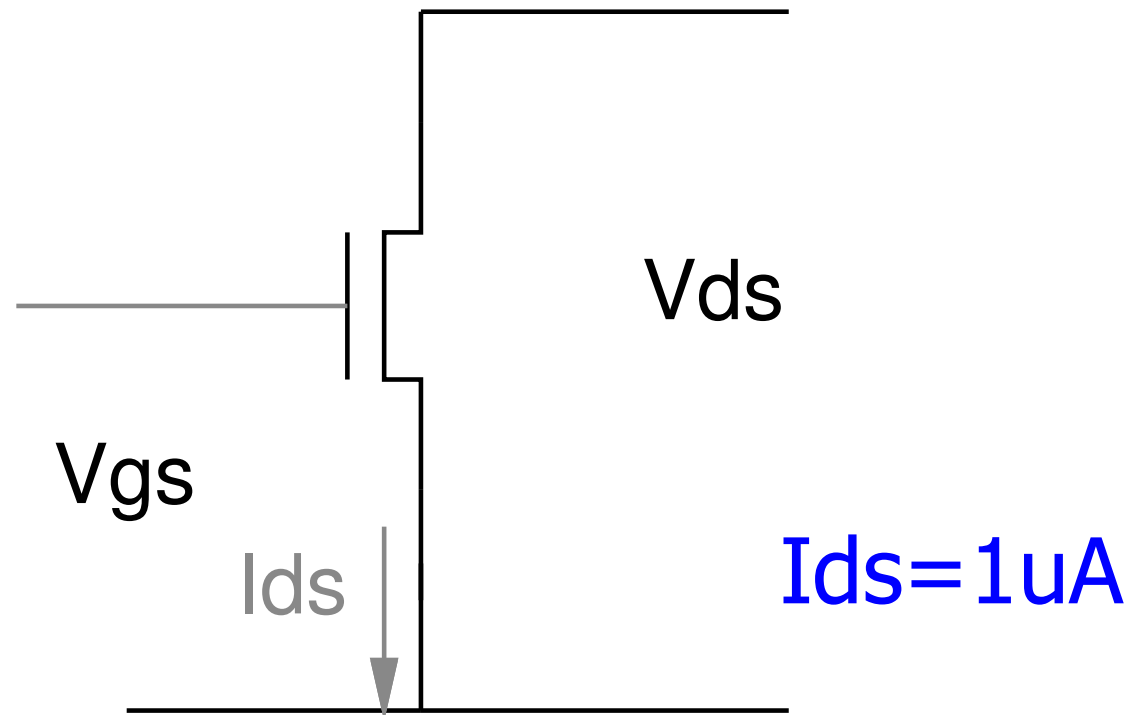
MOSFET – IV Characteristics





Preclass 2

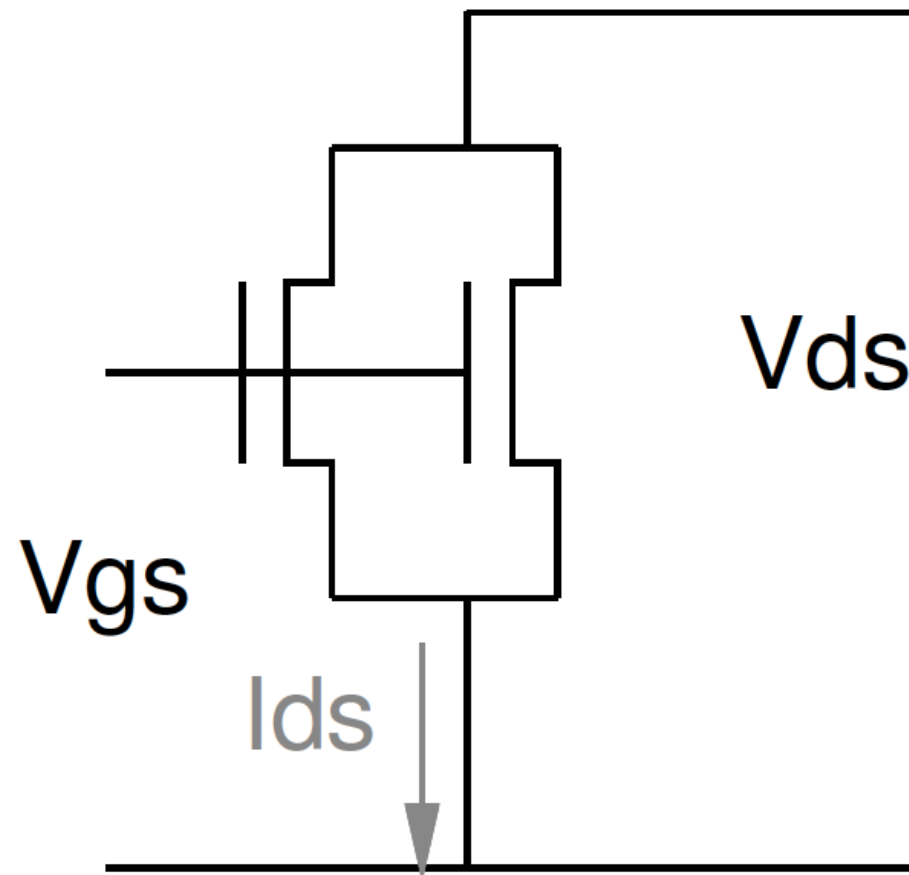
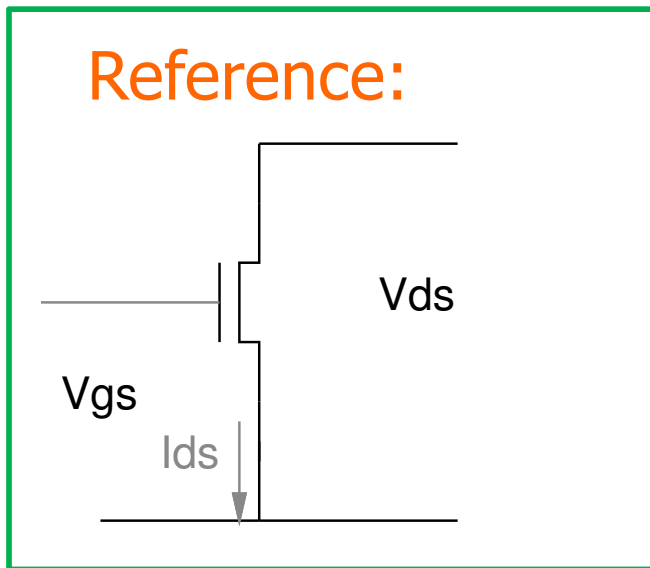
- Reference: I_{ds} for single transistor with V_{gs} and V_{ds} bias





Preclass 2

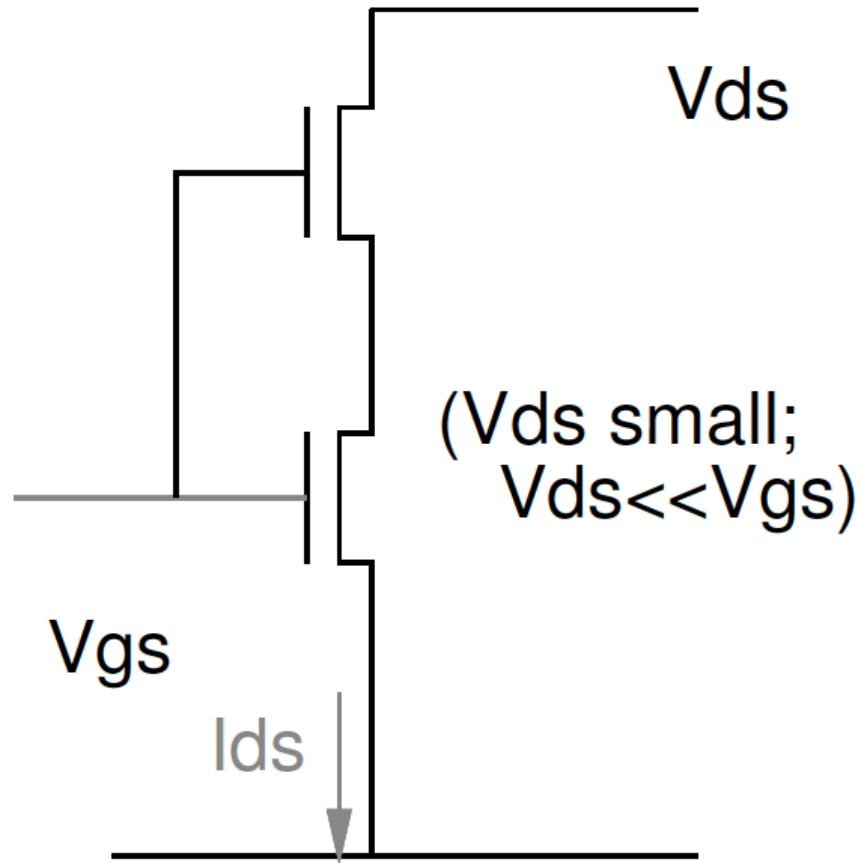
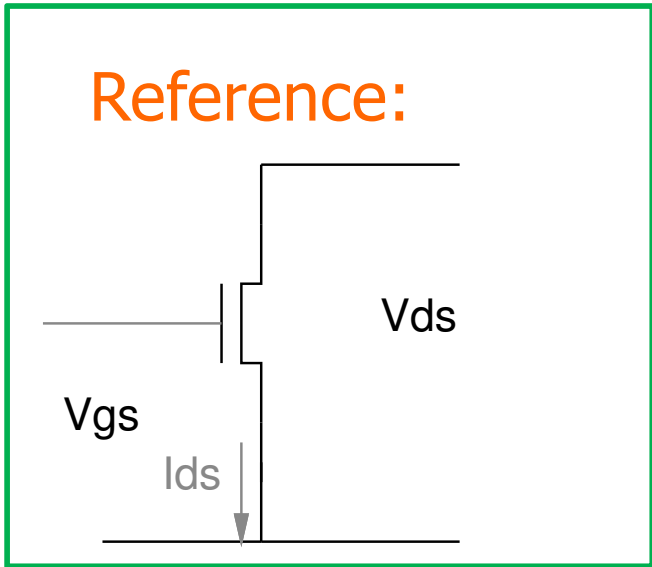
- I_{ds} for identical transistors in parallel?





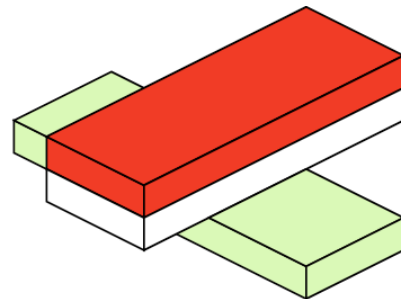
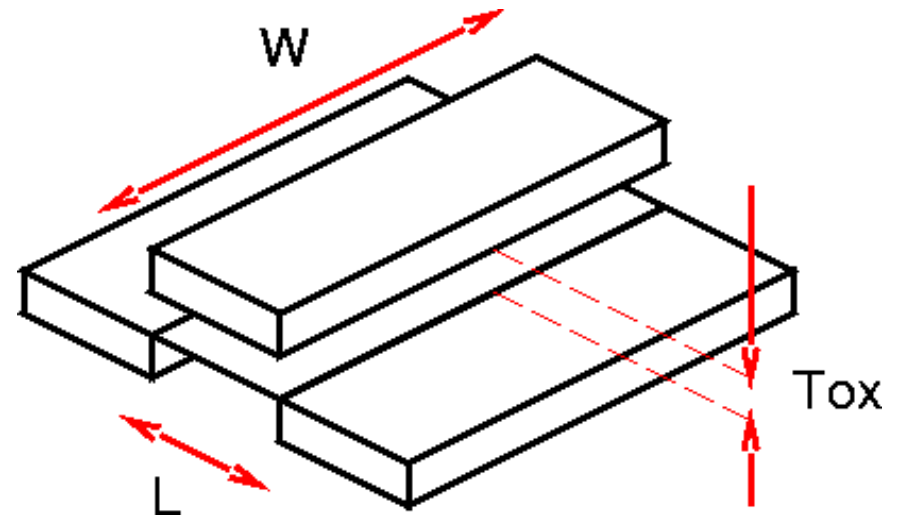
Preclass 2

- I_{ds} for identical transistors in series?
 - (V_{ds} small)



Dimensions

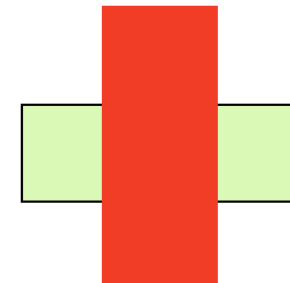
- ❑ Channel Length (L)
- ❑ Channel Width (W)
- ❑ Oxide Thickness (T_{ox})



Oblique



Side

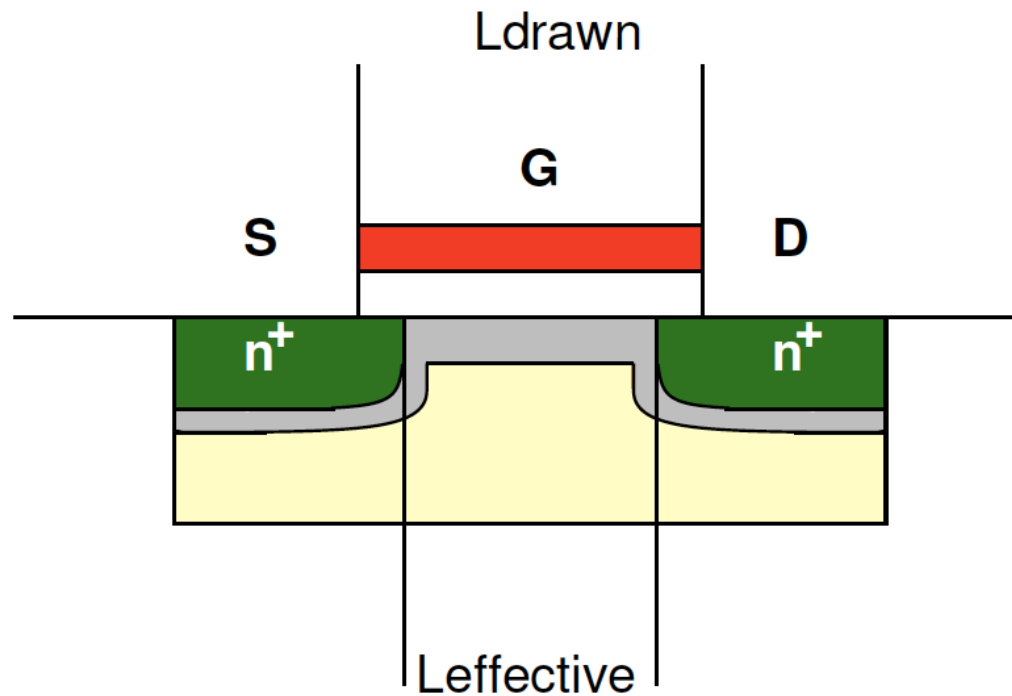


Top



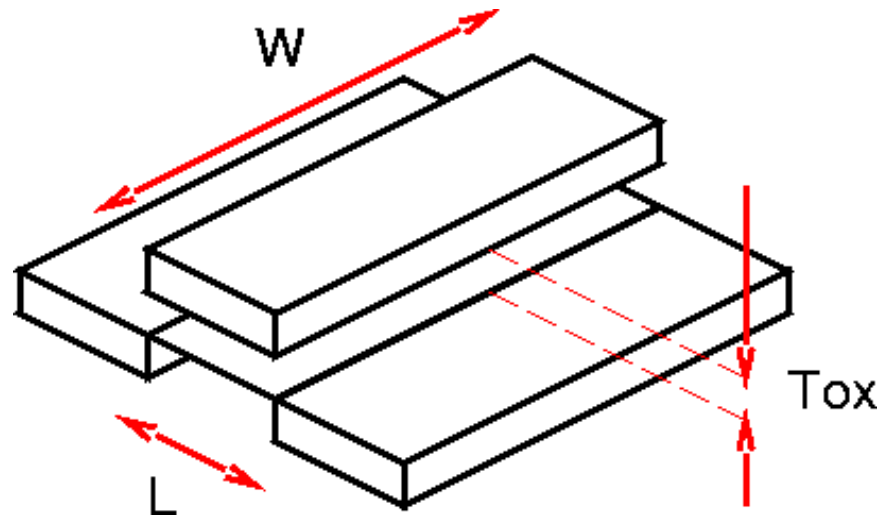
L_{drawn} vs. $L_{\text{effective}}$

- ❑ Doping not perfectly straight
- ❑ Spreads under gate
- ❑ Effective L smaller than draw gate width



Transistor Strength (W/L)

$$C_{OX} = \frac{\epsilon_{OX}}{t_{OX}}$$



$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$



Transistor Strength (W/L)

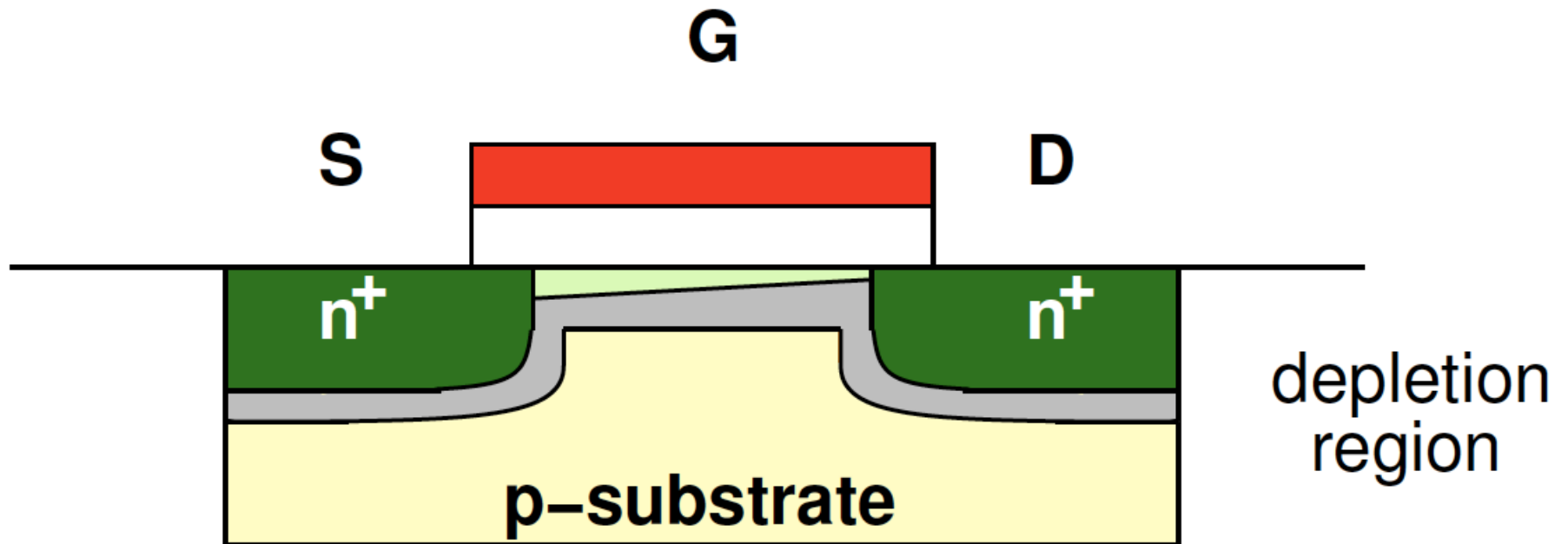
- Shape dependence match Resistance intuition
 - Wider = parallel resistors \rightarrow decrease R
 - Longer = series resistors \rightarrow increase R

$$R = \frac{\rho L}{A}$$

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

Channel Voltage

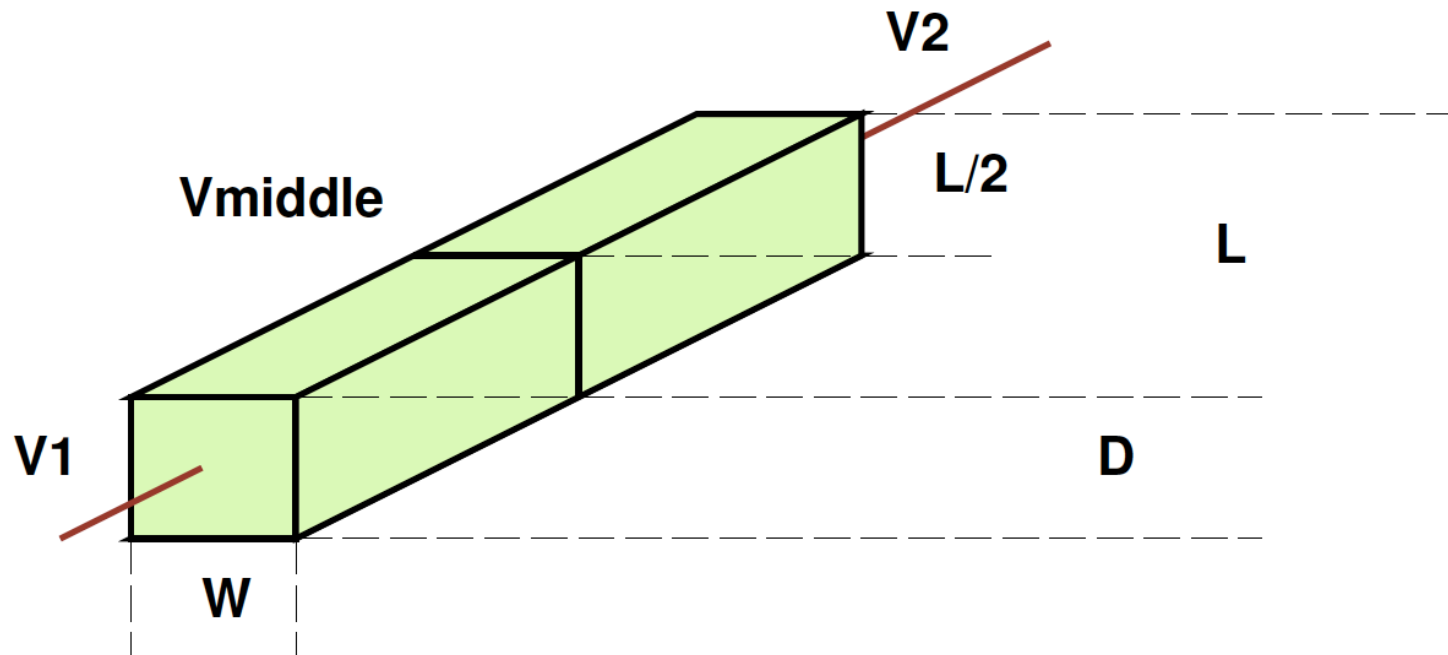
- ❑ Think of channel as resistor
- ❑ Voltage varies along channel





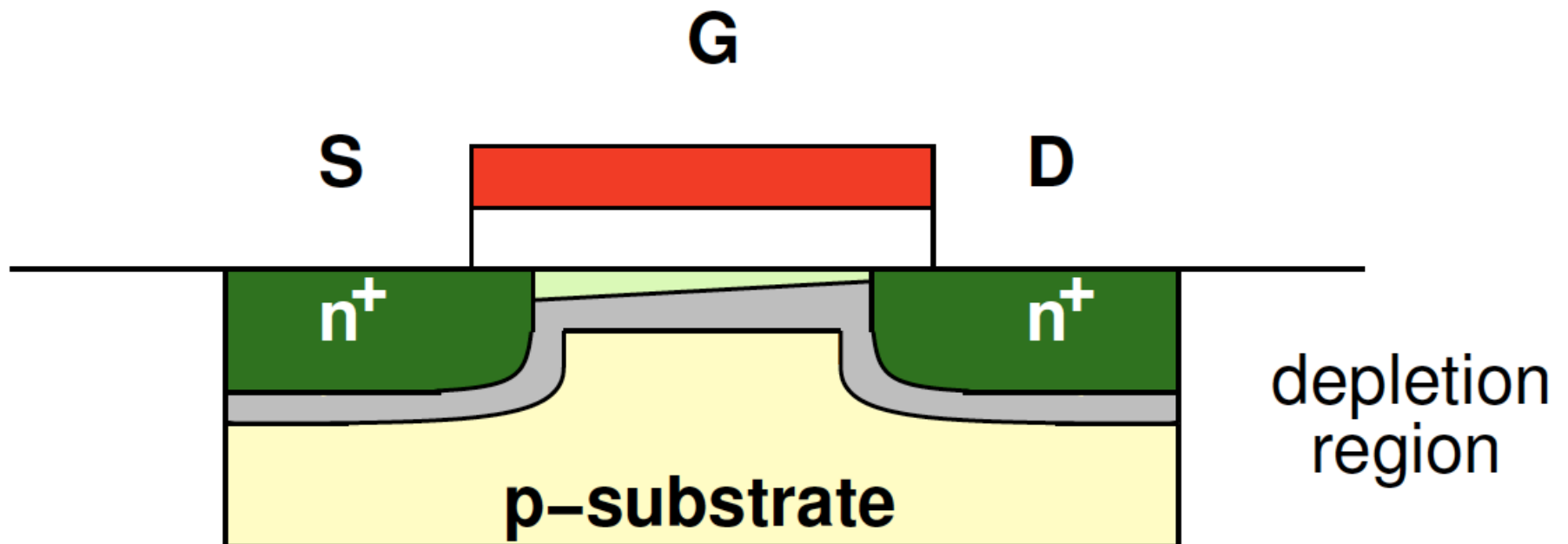
Preclass 3

- What is voltage in the middle of a resistive medium?
 - Relative to $V1$ and $V2$
 - halfway between terminals



Channel Voltage

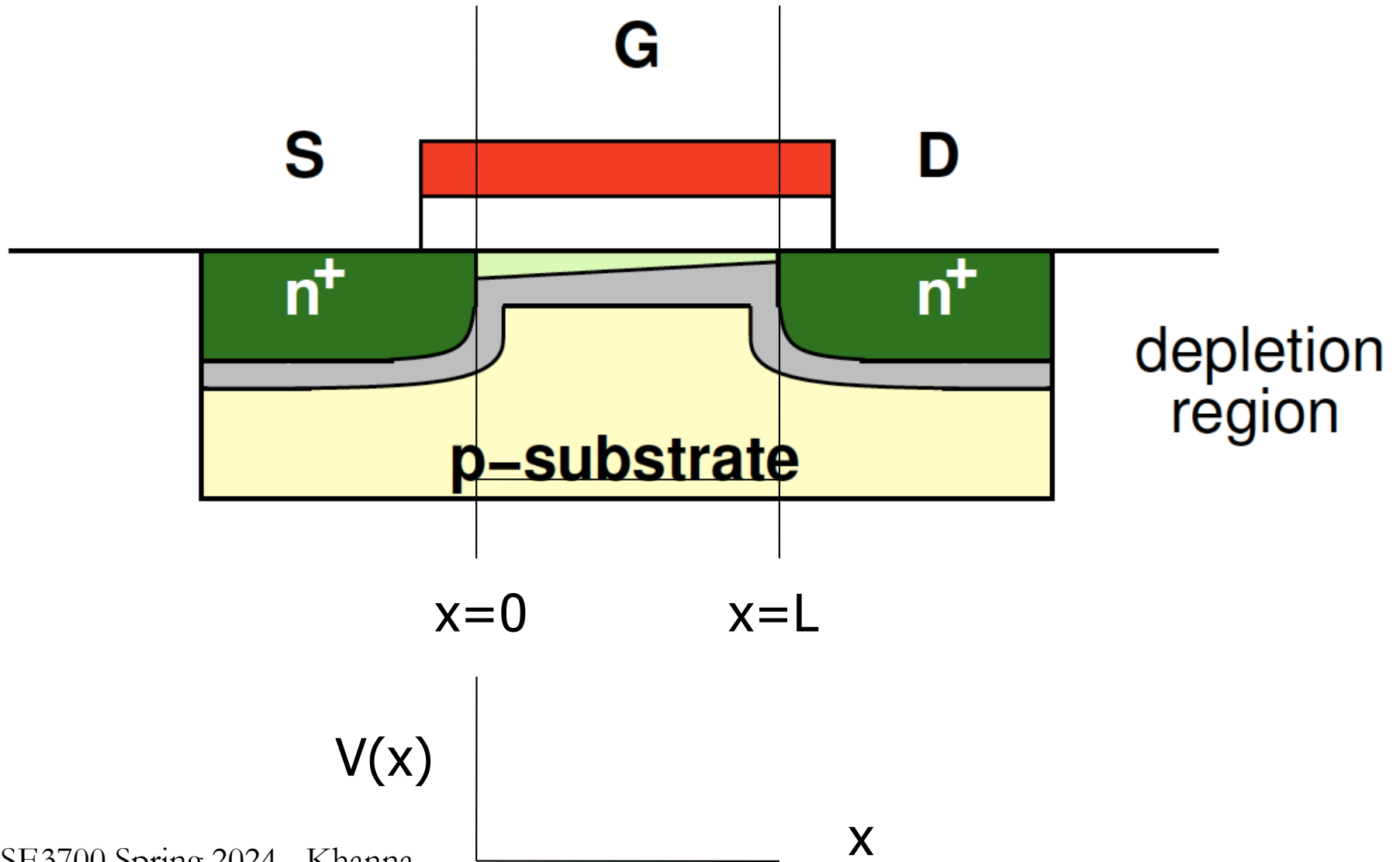
- Think of channel as resistor
- Voltage varies along channel
 - Serves as a voltage divider between V_S and V_D





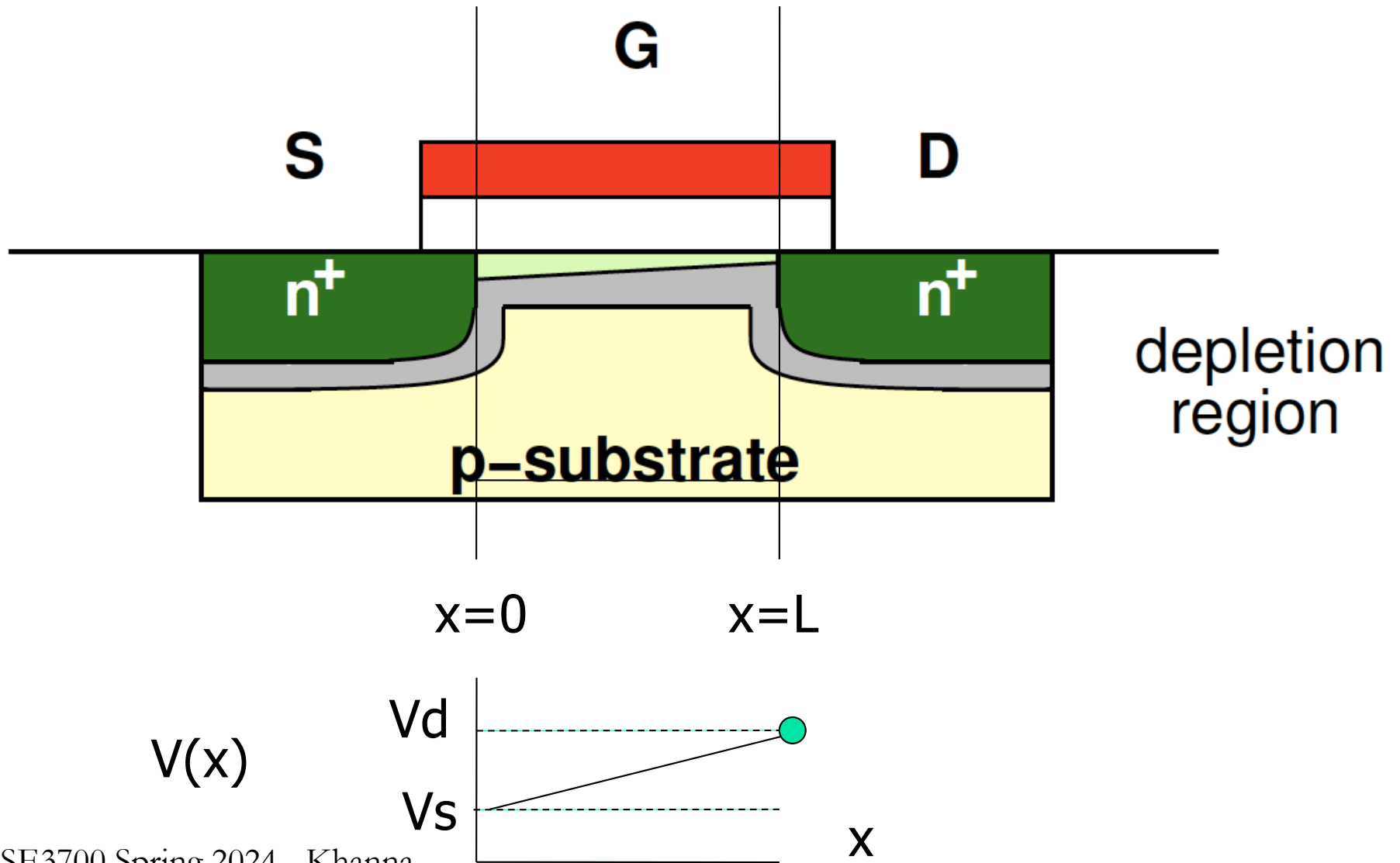
Voltage along Channel

- What does voltage along the channel look like?



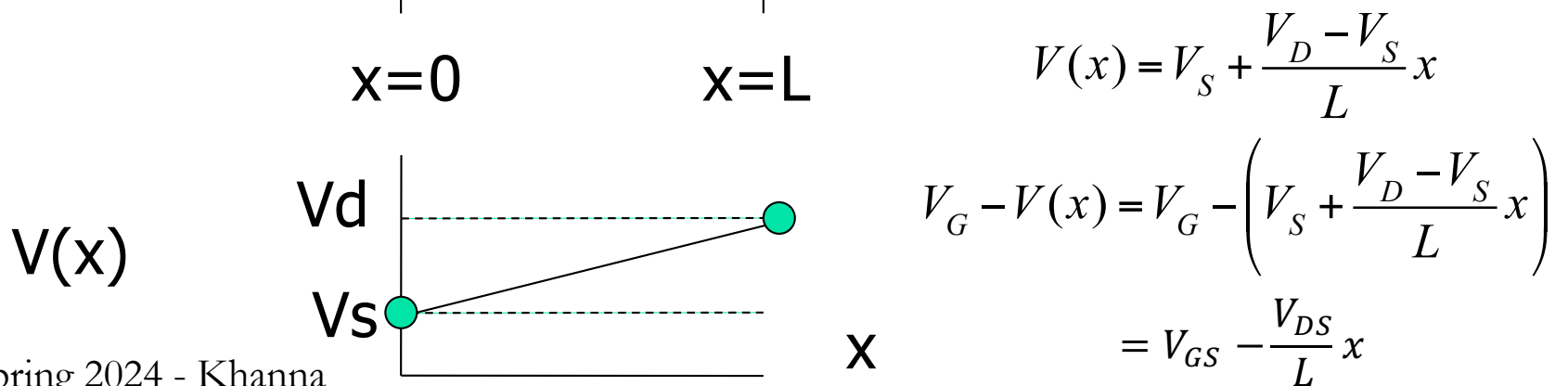
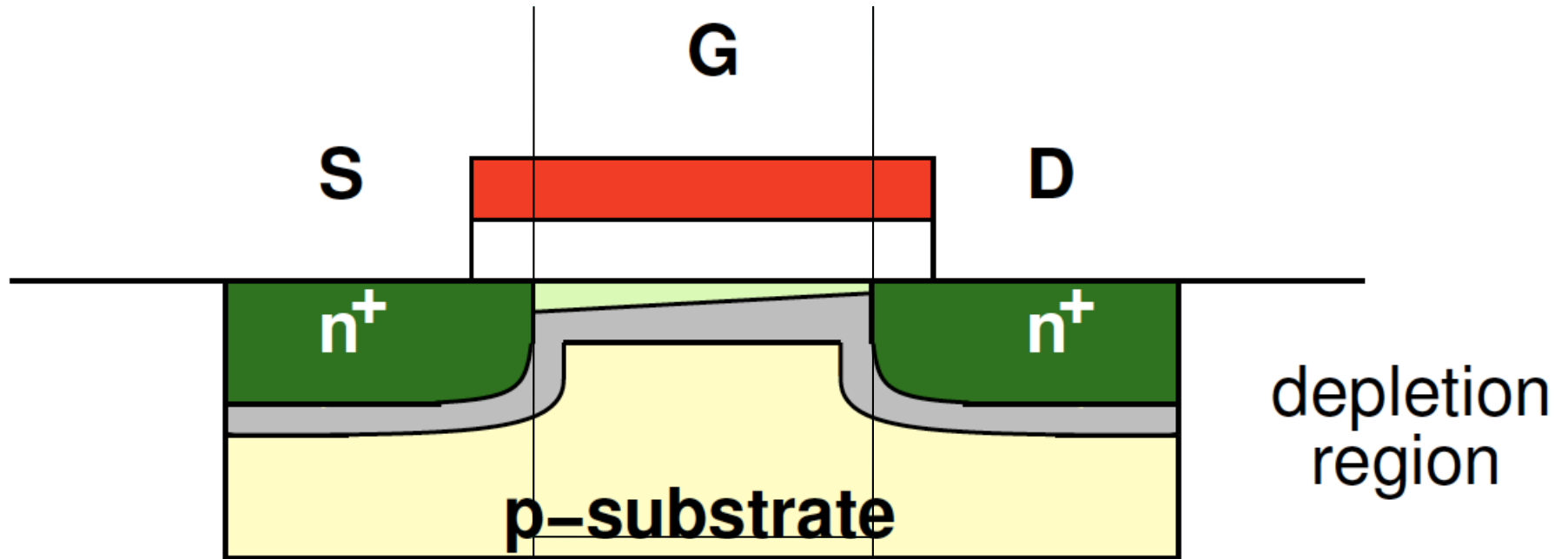
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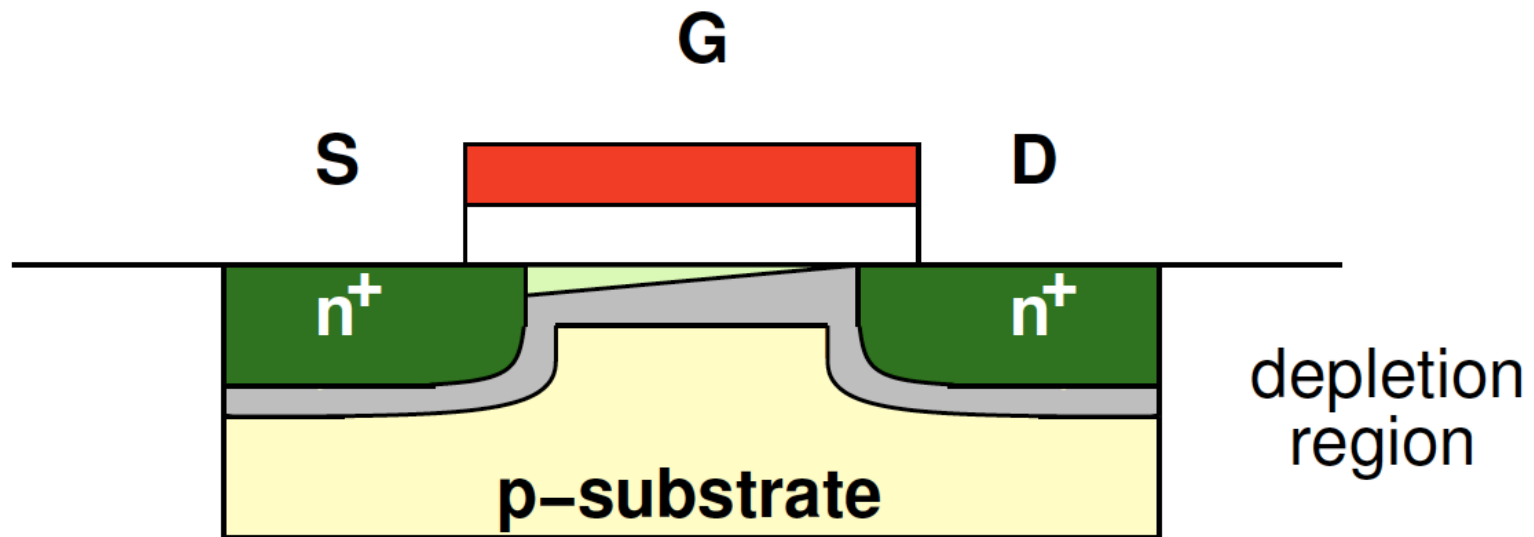
Voltage along Channel

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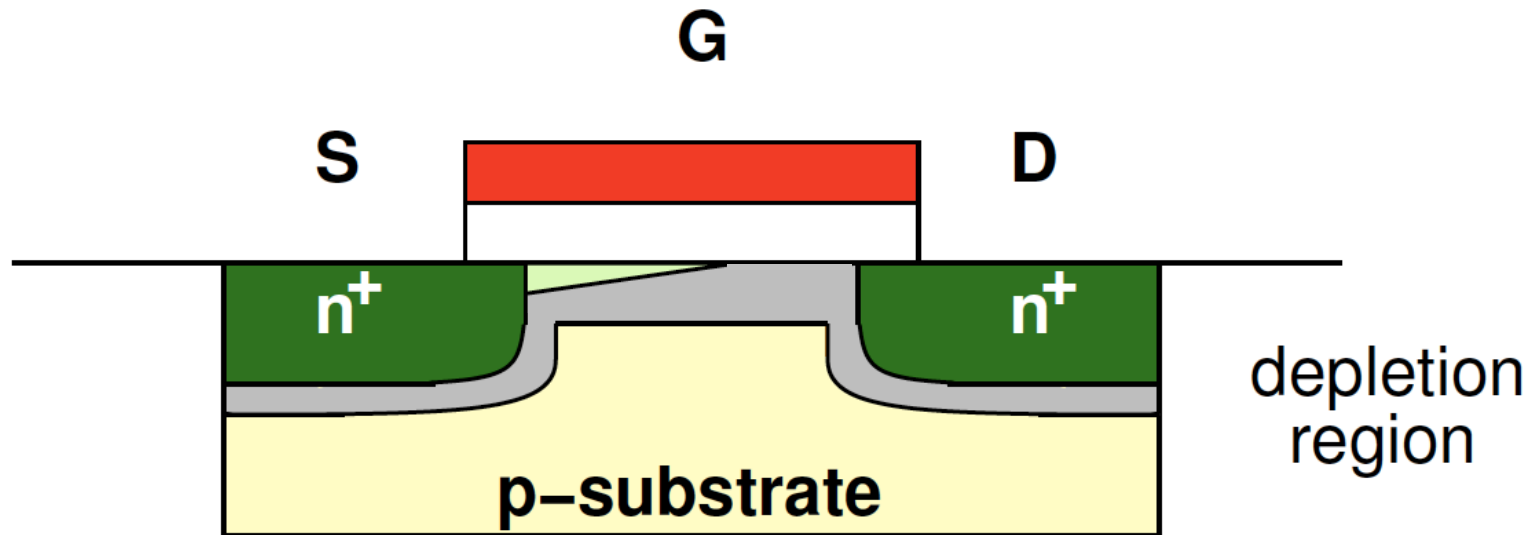
Channel Field

- When voltage gap $V_G - V_x$ drops below V_{th} , drops out of inversion
 - **Saturation Edge:** $V_{DS} = V_{GS} - V_{th} \rightarrow V_G - V_x(@ D) = ?$



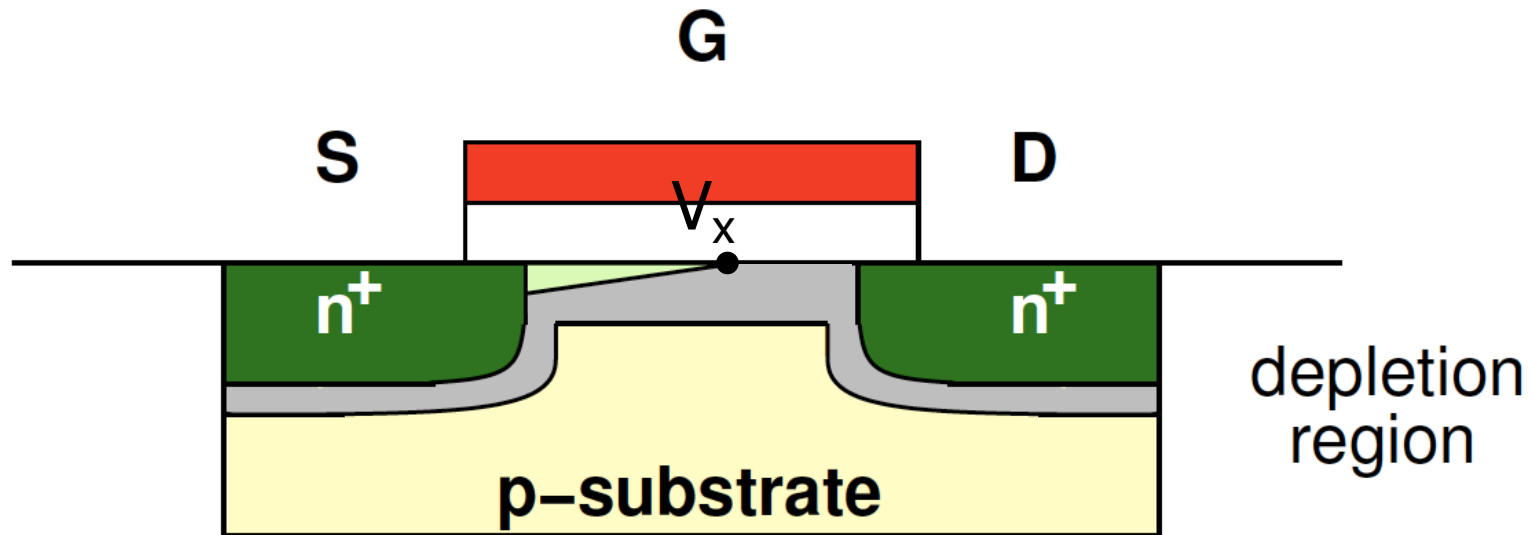
Channel Field

- When voltage gap $V_G - V_x$ drops below V_{th} , drops out of inversion
 - **Deep Saturation:** $V_{DS} > V_{GS} - V_{th} \rightarrow V_G - V_x(@ D) = ?$



Channel Field

- When voltage gap $V_G - V_x$ drops below V_{th} , drops out of inversion
 - **Deep Saturation:** $V_{DS} > V_{GS} - V_{th} \rightarrow V_G - V_x(@ D) < V_{th}$
Upper limit on current, channel is “pinched off”



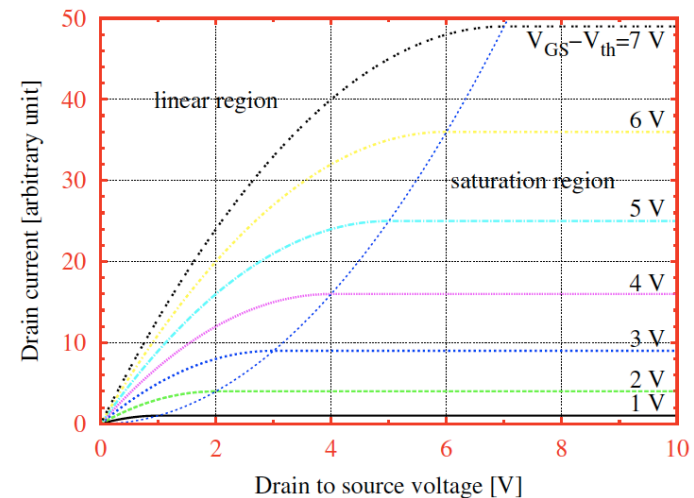


Pinch Off

- When voltage along the channel drops below V_{th} , the channel drops out of inversion
 - Occurs when: $V_G - V_X(@ D) < V_{th} \rightarrow V_{DS} > V_{GS} - V_{th}$

□ Conclusion:

- current cannot increase with V_{DS} once $V_{DS} > V_{GS} - V_T$
 - Not true! More later...





Saturation

- At edge of saturation, $V_{DS} = V_{GS} - V_T$

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

- Becomes:

Saturation

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$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

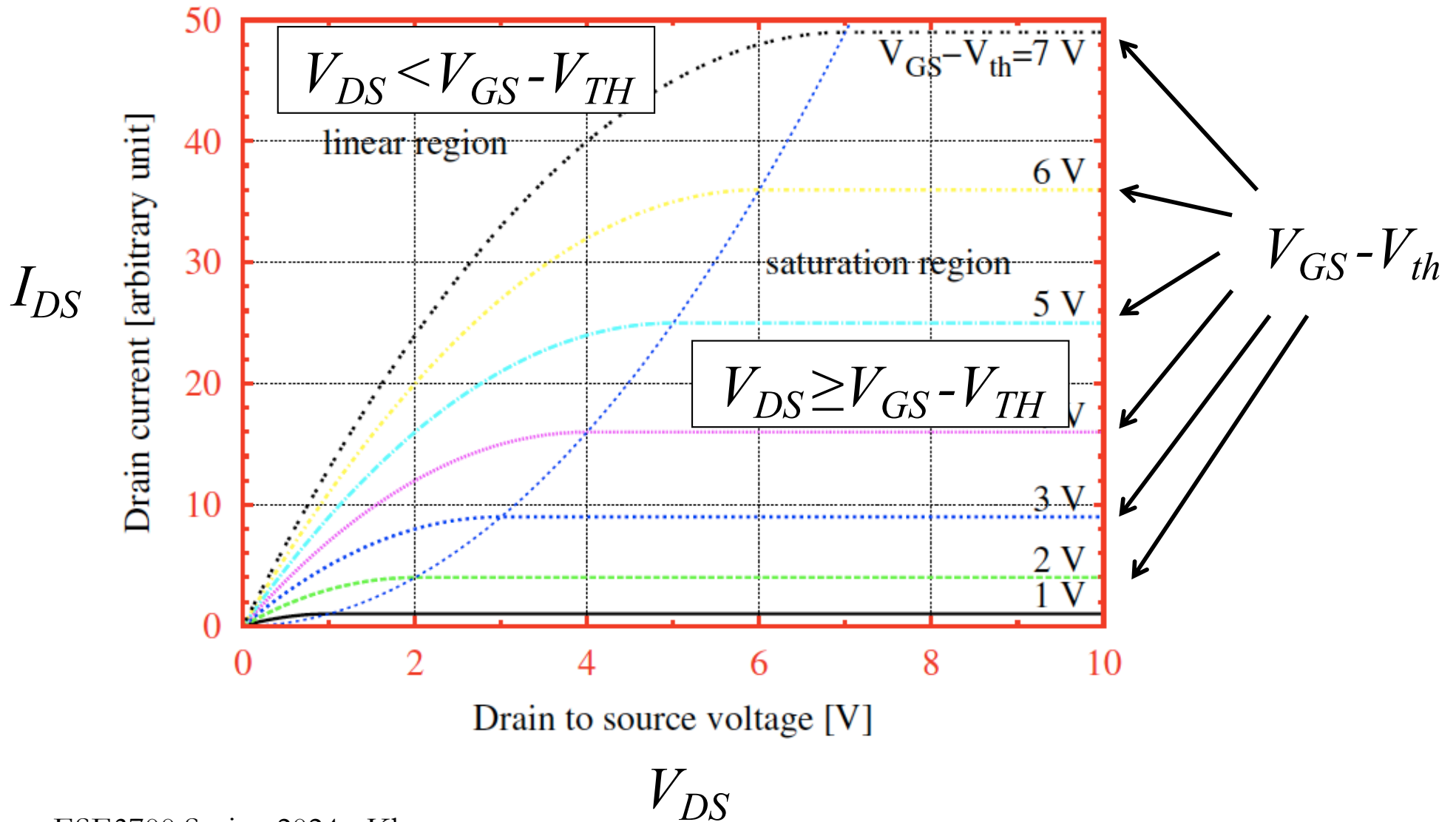
- Becomes:

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T)^2 - \frac{(V_{GS} - V_T)^2}{2} \right]$$

$$I_{DS} = \frac{\mu_n C_{OX}}{2} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T)^2 \right]$$



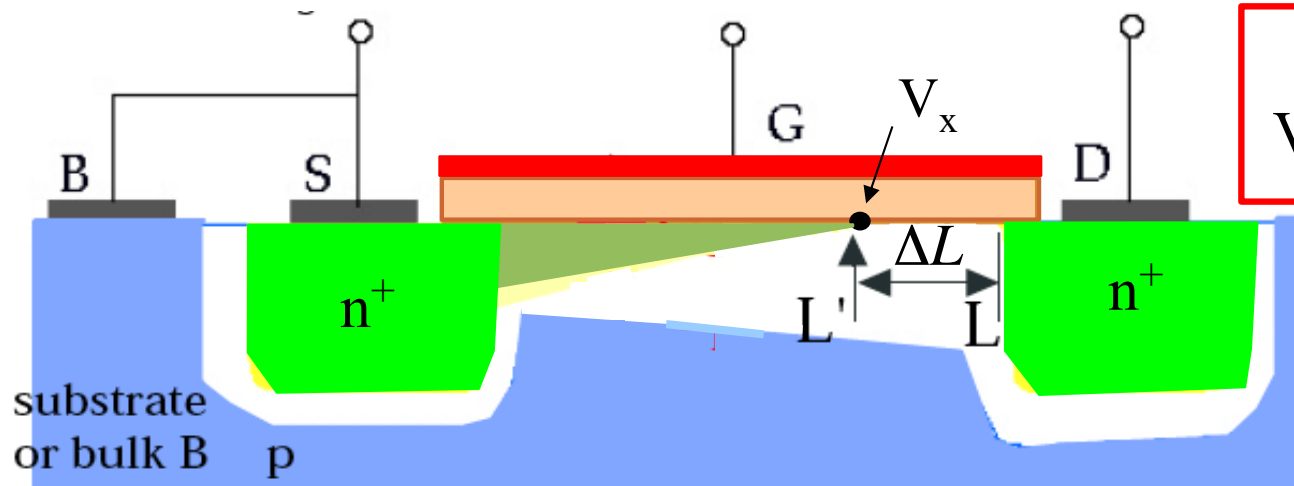
MOSFET – IV Characteristics



Channel Length Modulation



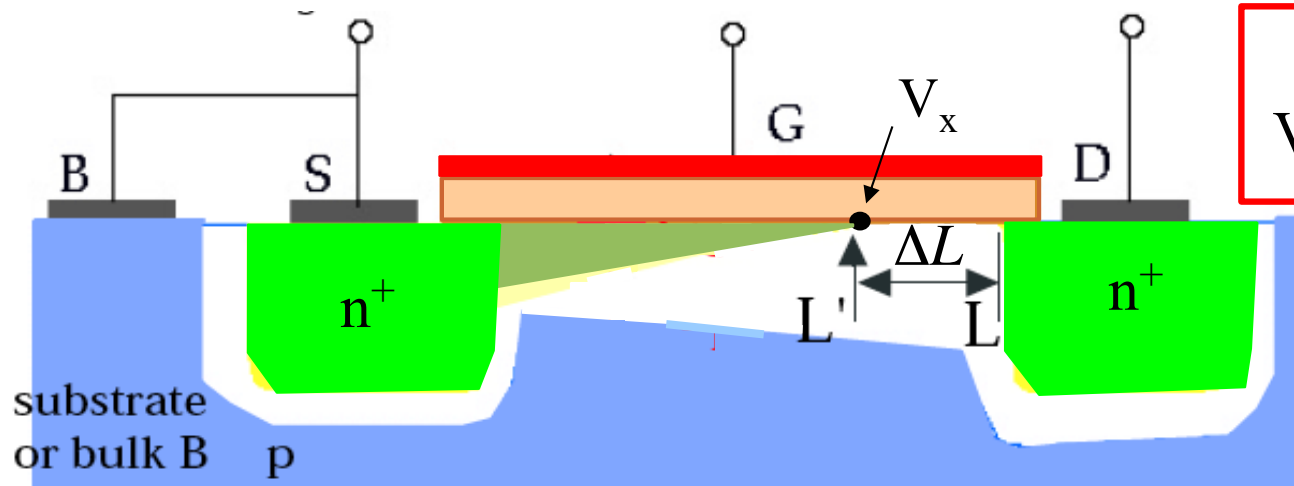
MOSFET IV Characteristics - Saturation



$$\begin{aligned} V_{GS} &> V_{T0} \\ V_{DS} &> V_{GS} - V_{T0} \end{aligned}$$

$$I_{DS} = \frac{\mu_n \cdot C_{ox}}{2} \frac{W}{L'} (V_{GS} - V_{T0})^2 = \frac{\mu_n \cdot C_{ox}}{2} \frac{W}{L - \Delta L} (V_{GS} - V_{T0})^2$$

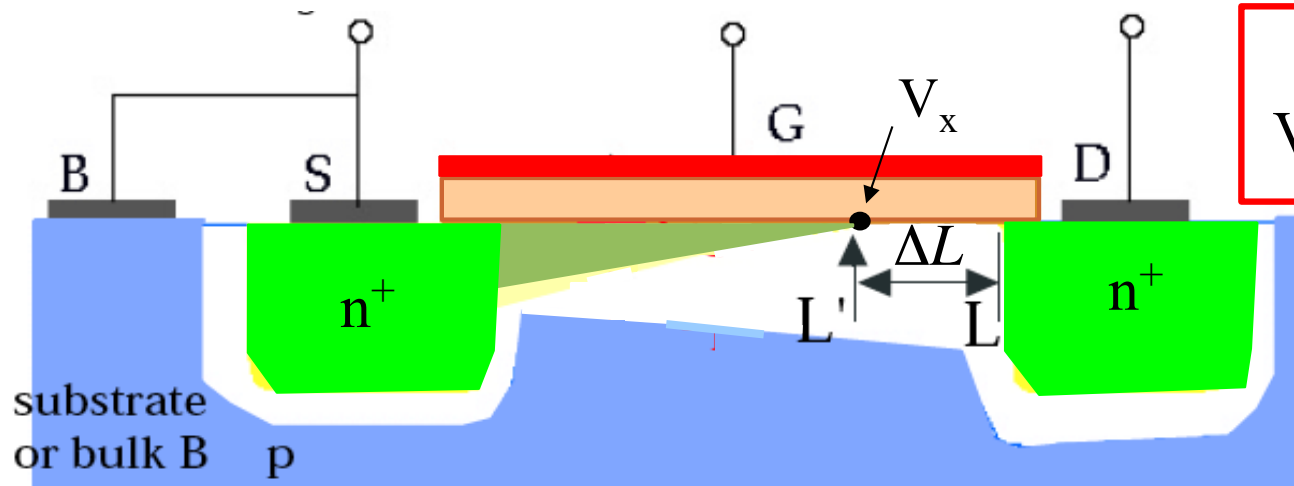
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MOSFET IV Characteristics - Saturation



$$\begin{aligned} V_{GS} &> V_{T0} \\ V_{DS} &> V_{GS} - V_{T0} \end{aligned}$$

$$I_{DS} = \frac{\mu_n \cdot C_{ox} \cdot W}{2 \cdot L} (V_{GS} - V_{T0})^2 \frac{1}{\left(1 - \frac{\Delta L}{L}\right)}$$

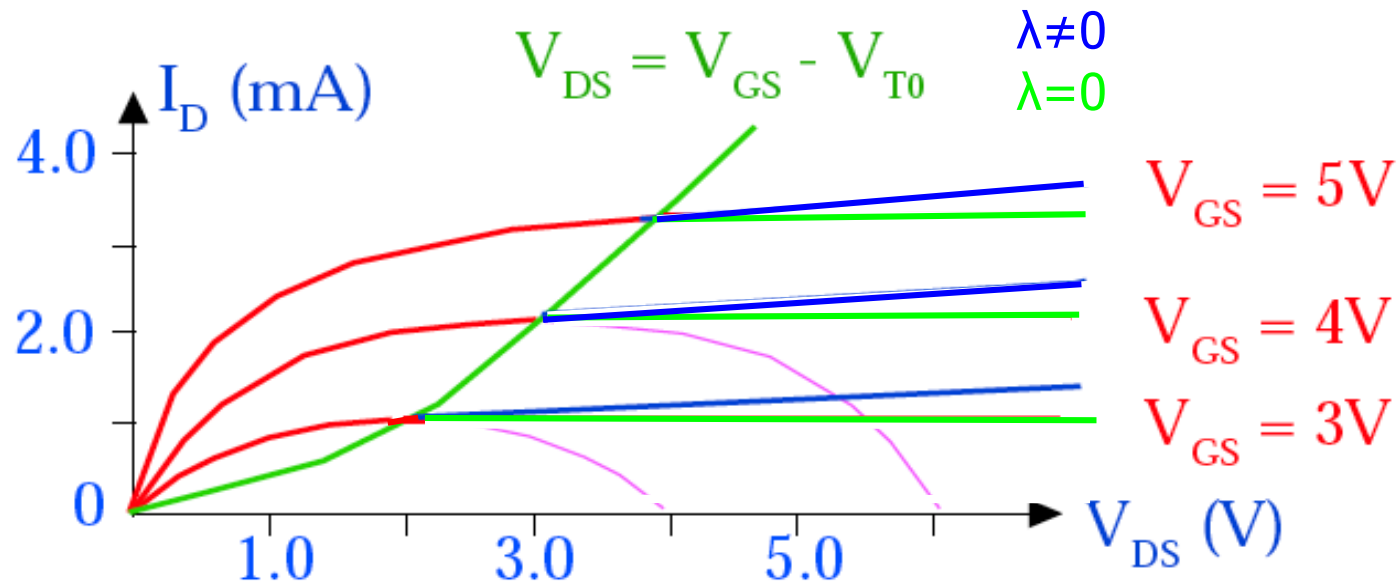
$$\Delta L \propto \sqrt{V_{DS} - (V_{GS} - V_{T0})} \xrightarrow{\text{empirically}} 1 - \frac{\Delta L}{L} \approx 1 - \lambda \cdot V_{DS}$$

$$\text{If } \lambda \cdot V_{DS} \ll 1, \quad \left(1 - \frac{\Delta L}{L}\right)^{-1} \approx 1 + \lambda \cdot V_{DS}$$

MOSFET IV Characteristics

Linear Region:
$$I_D = \mu_n \cdot C_{ox} \frac{W}{L} \left((V_{GS} - V_{T0})V_{DS} - \frac{V_{DS}^2}{2} \right)$$

Saturation Region:
$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \frac{W}{L} (V_{GS} - V_{T0})^2 (1 + \lambda \cdot V_{DS})$$



MOSFET IV Characteristics

Linear Region:

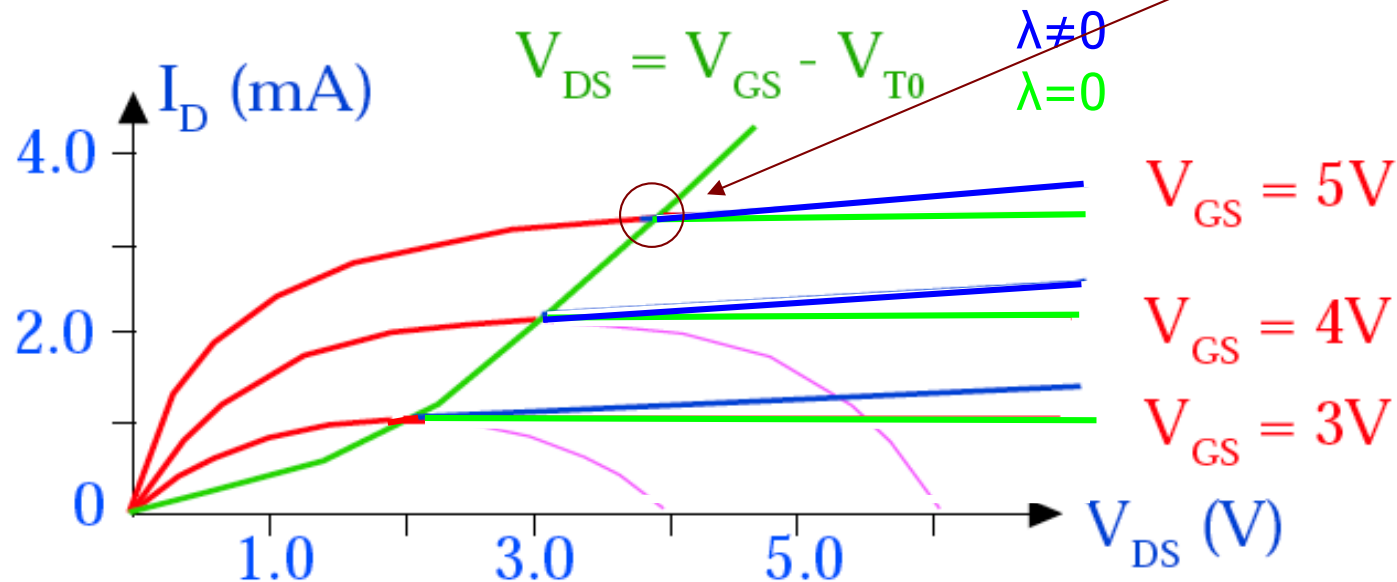
$$I_D = \mu_n \cdot C_{ox} \frac{W}{L} \left((V_{GS} - V_{T0})V_{DS} - \frac{V_{DS}^2}{2} \right)$$

Saturation Region:

$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \frac{W}{L} (V_{GS} - V_{T0})^2 (1 + \lambda \cdot V_{DS})$$

DISCONTINUOUS!

@ $V_{DS} = V_{GS} - V_T$



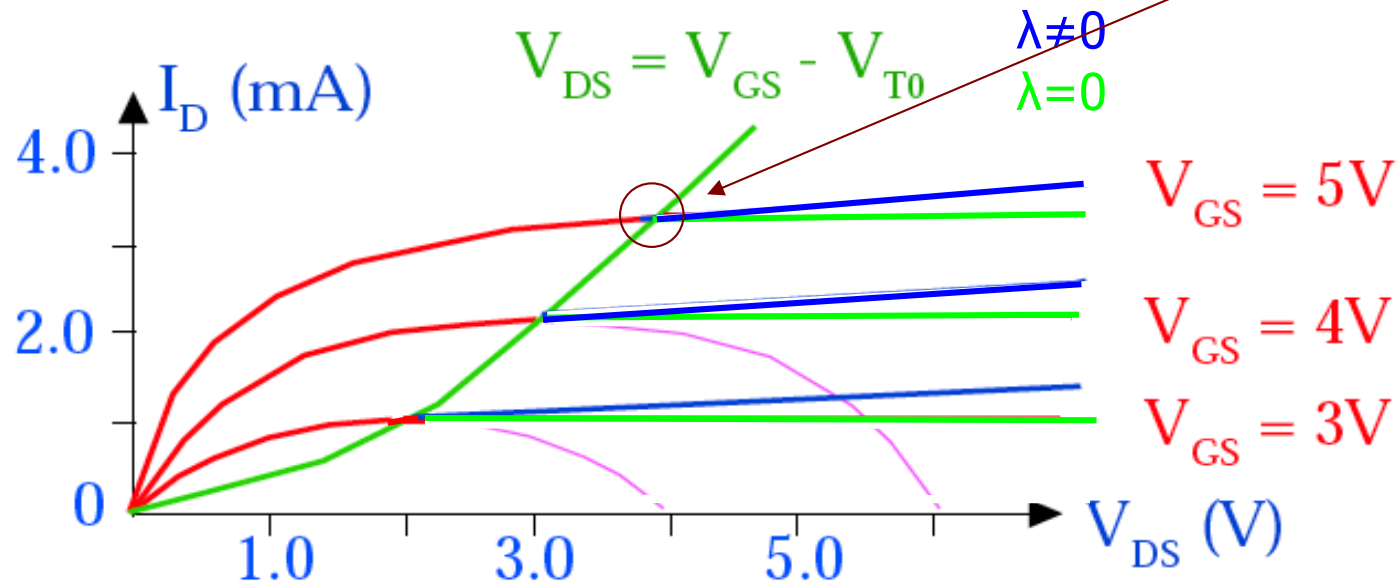
MOSFET IV Characteristics

Linear Region:
$$I_D = \mu_n \cdot C_{ox} \frac{W}{L} \left((V_{GS} - V_{T0})V_{DS} - \frac{V_{DS}^2}{2} \right) (1 + \lambda \cdot V_{DS})$$

Saturation Region:
$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \frac{W}{L} (V_{GS} - V_{T0})^2 (1 + \lambda \cdot V_{DS})$$

DISCONTINUOUS!

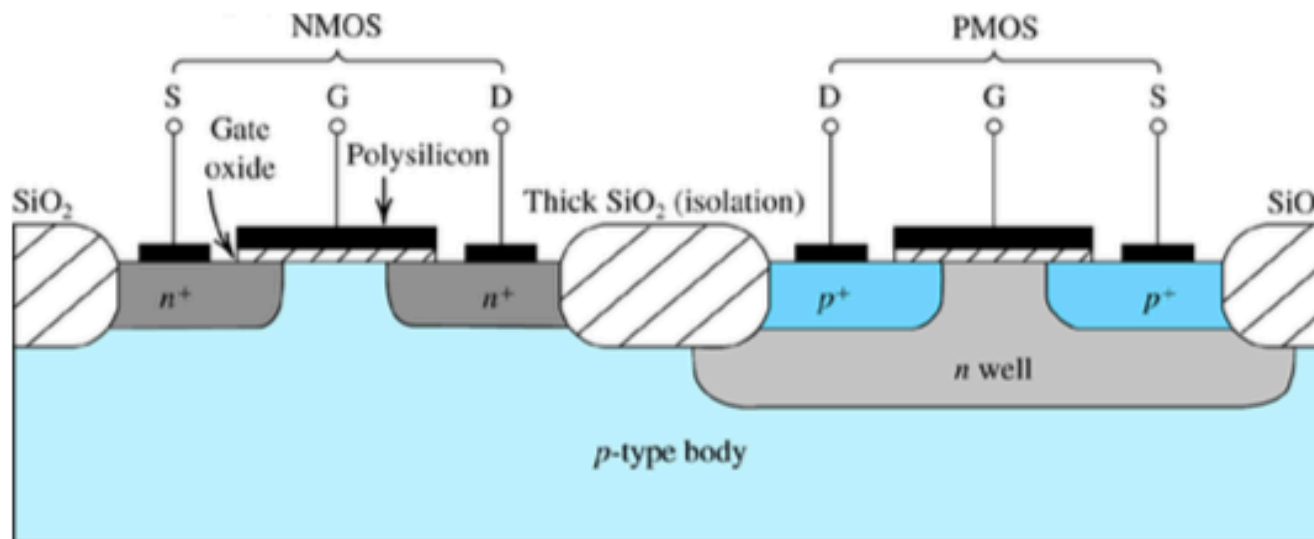
@ $V_{DS} = V_{GS} - V_T$





pMOS Device

- ❑ Analogous phenomena to NMOS
- ❑ Opposite polarity
 - Negative V_{th} , λ
- ❑ Reason based on oppositely charged carriers

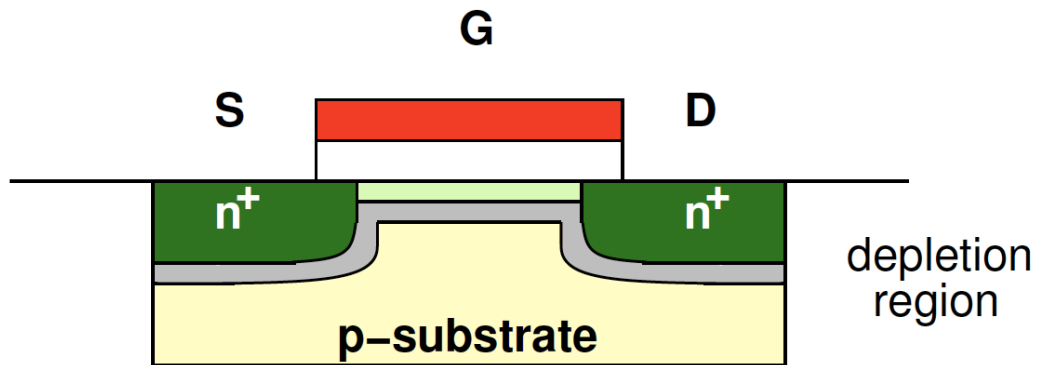


Above Threshold

Summary

Linear Region

- $V_{GS} > V_{th}$ and V_{DS} small



$$C_{OX} = \frac{\epsilon_{OX}}{t_{OX}}$$

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_{th}) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

Saturation

- In saturation, $V_{DS\text{-effective}} = V_x = V_{GS} - V_T$

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$$

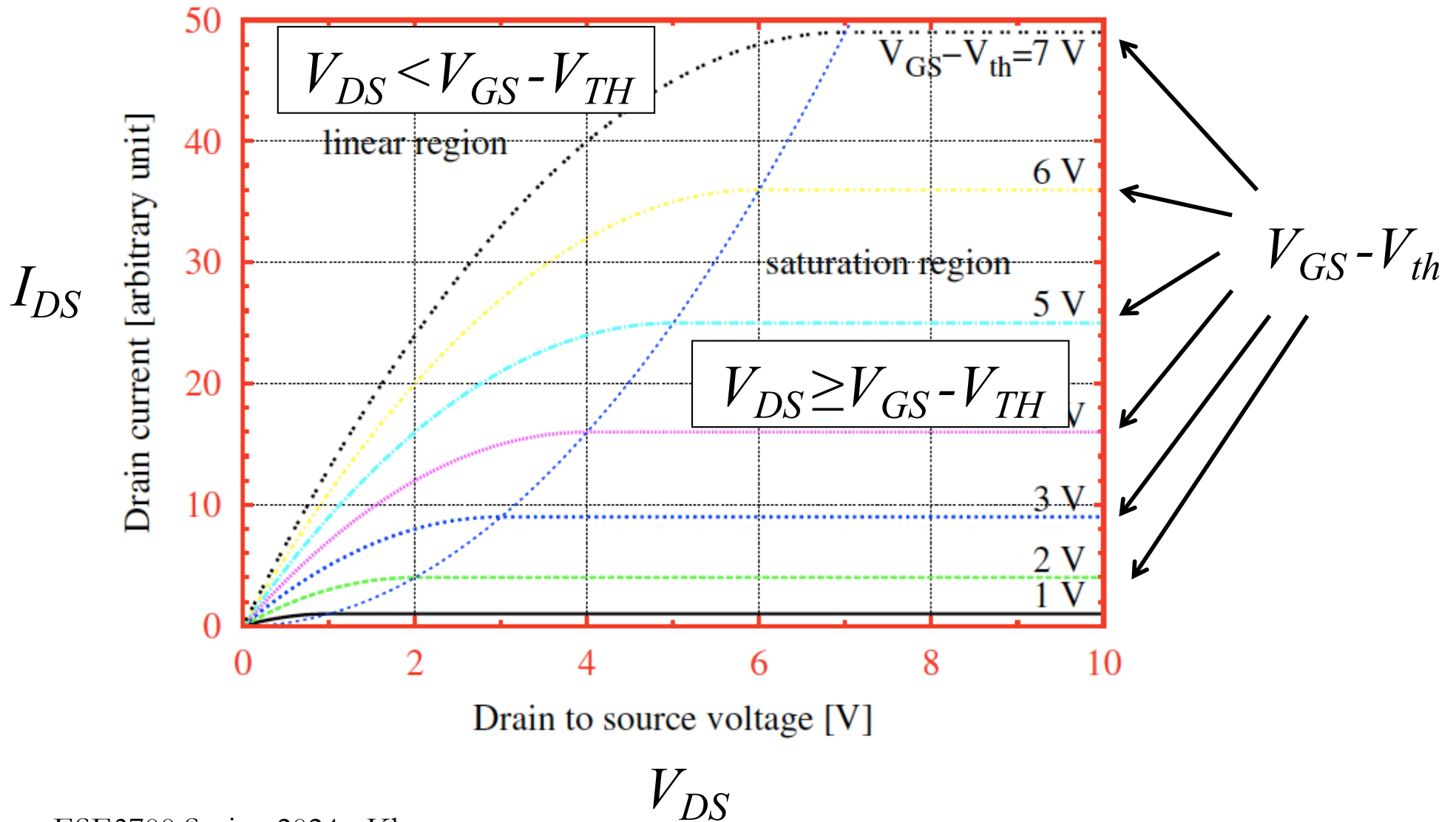
- Becomes:

$$I_{DS} = \mu_n C_{OX} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T)^2 - \frac{(V_{GS} - V_T)^2}{2} \right]$$

$$I_{DS} = \frac{\mu_n C_{OX}}{2} \left(\frac{W}{L} \right) \left[(V_{GS} - V_T)^2 \right]$$



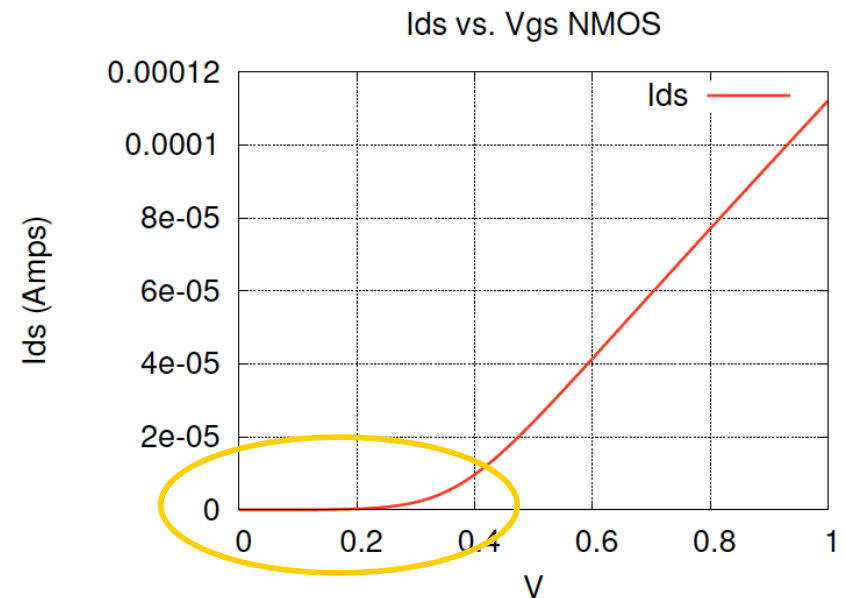
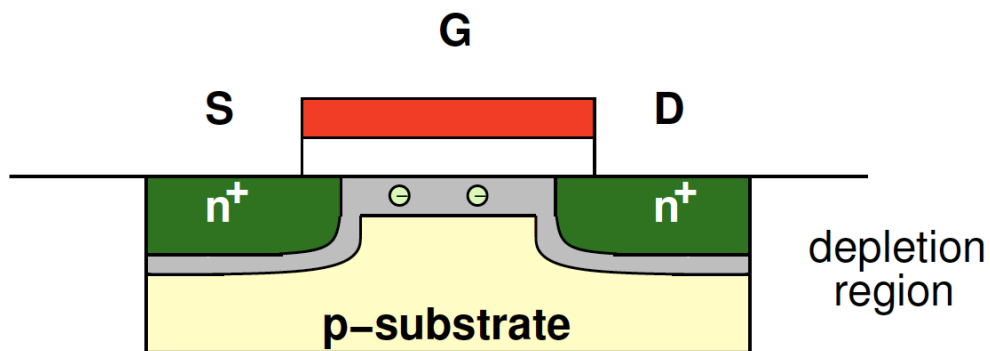
MOSFET – IV Characteristics



Subthreshold

Below Threshold

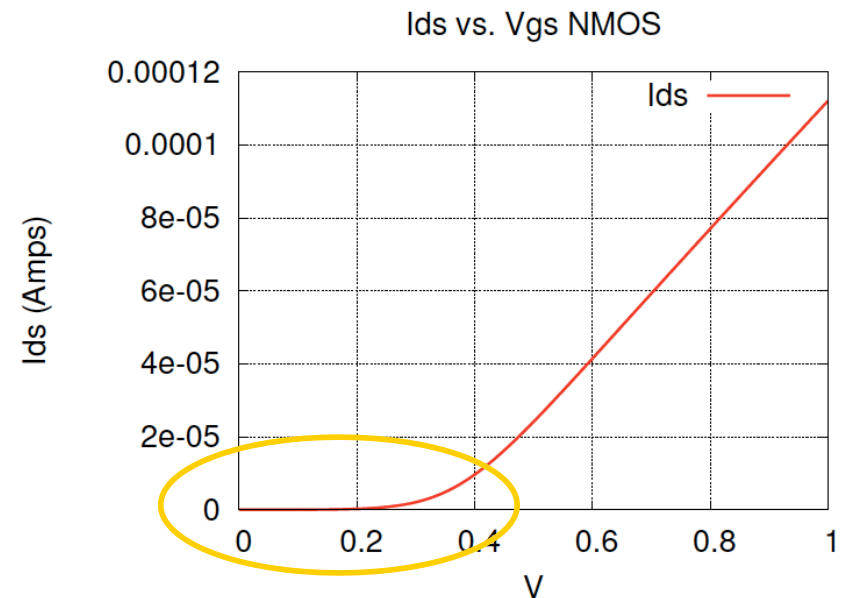
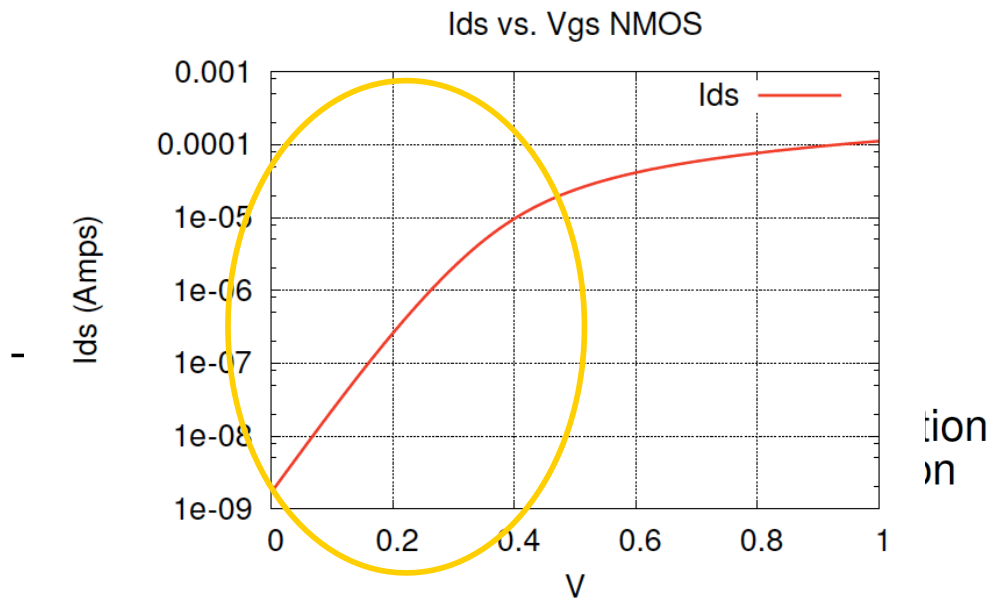
- ❑ Transition from insulating to conducting is non-linear, but not abrupt
- ❑ Current does flow below threshold
 - But exponentially dependent on V_{GS}





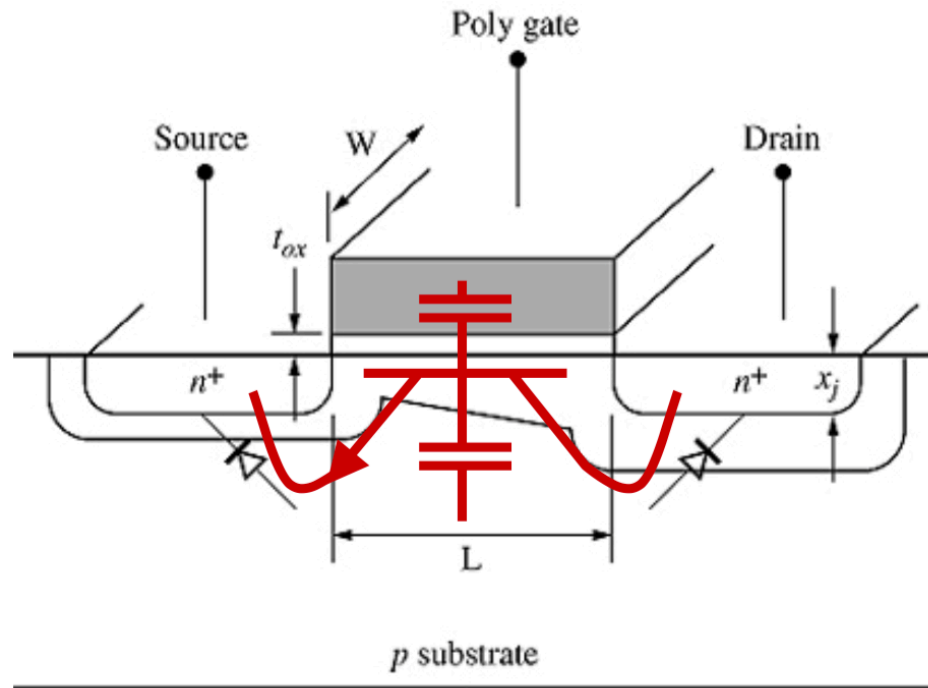
Below Threshold

- ❑ Transition from insulating to conducting is non-linear, but not abrupt
- ❑ Current does flow below threshold
 - But exponentially dependent on V_{GS}



Parasitic NPN BJT

- ❑ We have an NPN sandwich, mobile minority carriers in the P region
- ❑ This is a BJT!
 - Except that the base potential is here controlled through a capacitive divider, and not directly an electrode





Subthreshold

If $V_{GS} < V_{th}$,

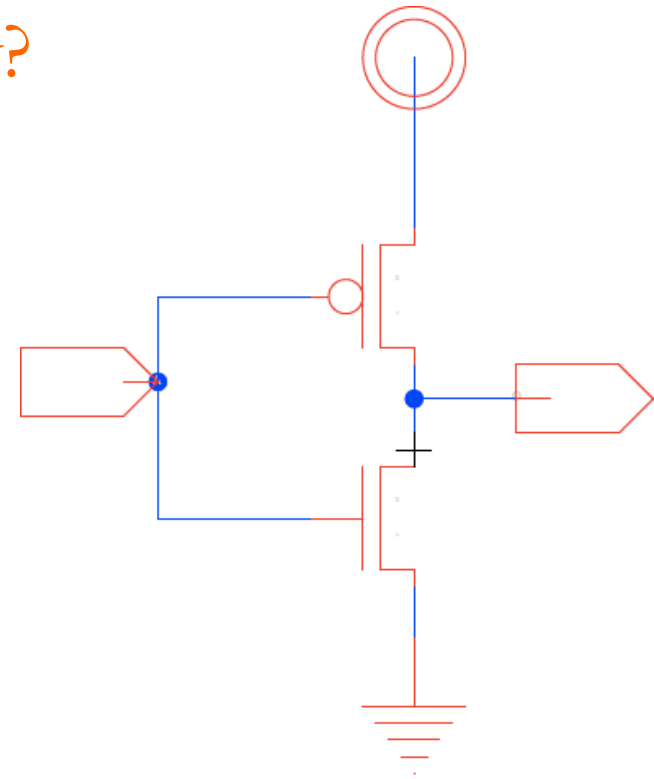
$$I_{DS} = I_S \left(\frac{W}{L} \right) e^{\left(\frac{V_{GS} - V_{th}}{nkT/q} \right)}$$

- Current is from the parasitic NPN BJT transistor when gate is below threshold and there is no conducting channel
 - n is the capacitive divider between parasitic capacitances
 - Typically $1 < n < 1.5$

$$n = \frac{C_{js} + C_{ox}}{C_{ox}}$$

Steady State (Preclass 4)

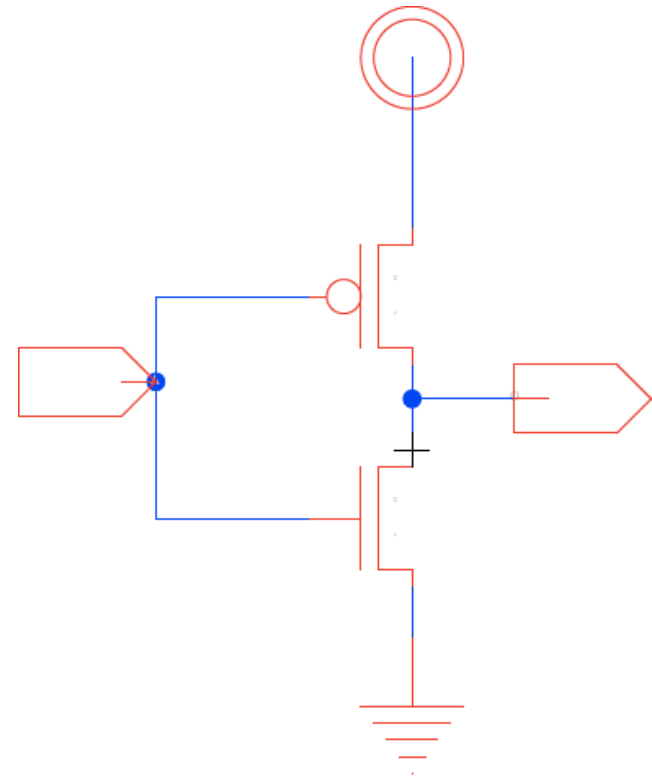
- ❑ What current flows in steady state?
- ❑ What causes (and determines) the magnitude of current flow?
- ❑ Which device?





Leakage

- Call this steady-state current flow leakage
 - $I_{ds,leakage}$

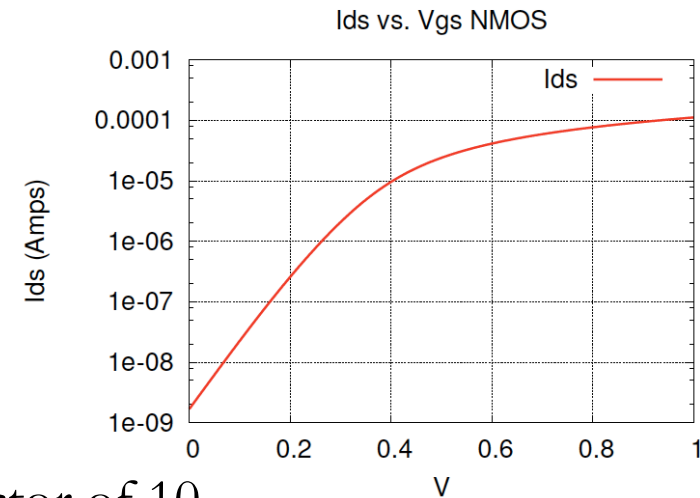


Subthreshold Slope Factor

- Exponent in V_{GS} determines how steep the turnon is

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$

- Units: V/decade
 - Every S Volts, I_{DS} is scaled by factor of 10

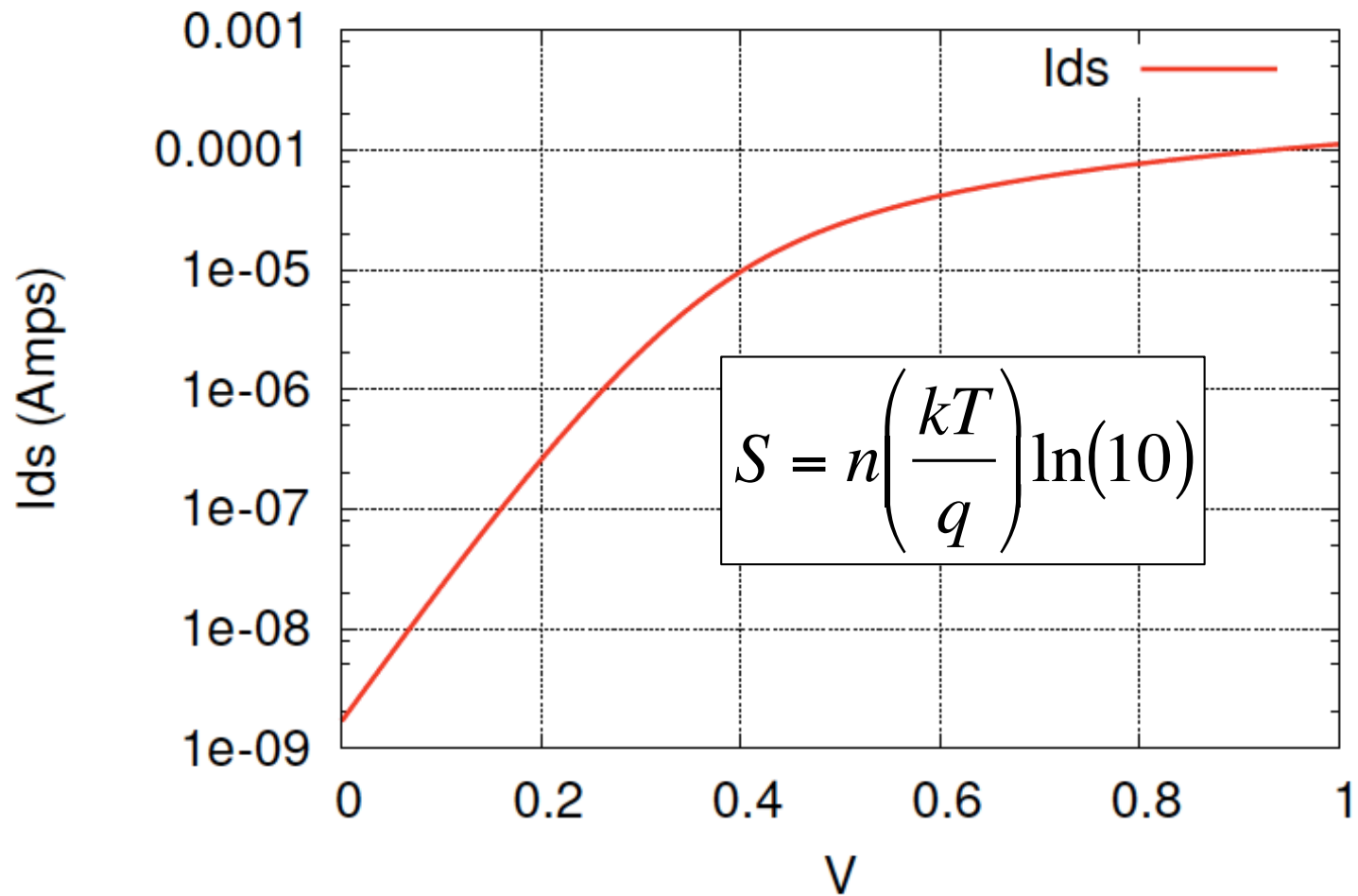


$$I_{DS} = I_S \left(\frac{W}{L} \right) e^{\left(\frac{V_{GS} - V_{th}}{nkT/q} \right)}$$



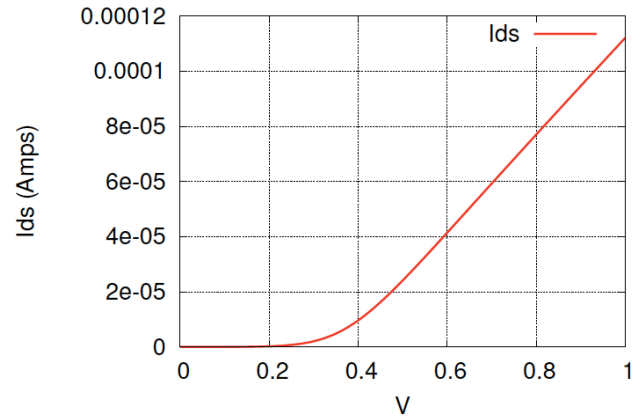
I_{DS} vs. V_{GS}

Ids vs. Vgs NMOS



(Logscale)

Ids vs. Vgs NMOS



Subthreshold Slope Factor

- Exponent in V_{GS} determines how steep the turnon is

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$

- Units: V/dec
- Every S Volts, I_{DS} is scaled by factor of 10
- n – depends on parasitic capacitance divider
 - $n=1 \rightarrow S=60\text{mV}$ at Room Temp. (ideal)
 - $n=1.5 \rightarrow S=90\text{mV}$
 - Single gate structure showing $S=90\text{-}110\text{mV}$

$$n = \frac{C_{js} + C_{ox}}{C_{ox}}$$



Subthreshold Slope Factor (Preclass 5)

- If $S=100\text{mV}$ and $V_{\text{th}}=300\text{mV}$,
what is $I_{\text{ds}}(V_{\text{gs}}=300\text{mV})/I_{\text{ds}}(V_{\text{gs}}=0\text{V})$?

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$



Subthreshold Slope Factor (Preclass 5)

- If $S=100\text{mV}$ and $V_{\text{th}}=300\text{mV}$,
what is $I_{\text{ds}}(V_{\text{gs}}=300\text{mV})/I_{\text{ds}}(V_{\text{gs}}=0\text{V})$?

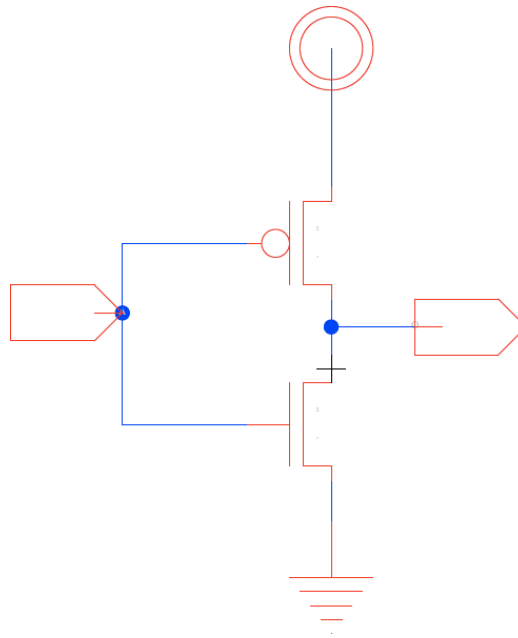
- What if $S=60\text{mV}$?

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$



Approach

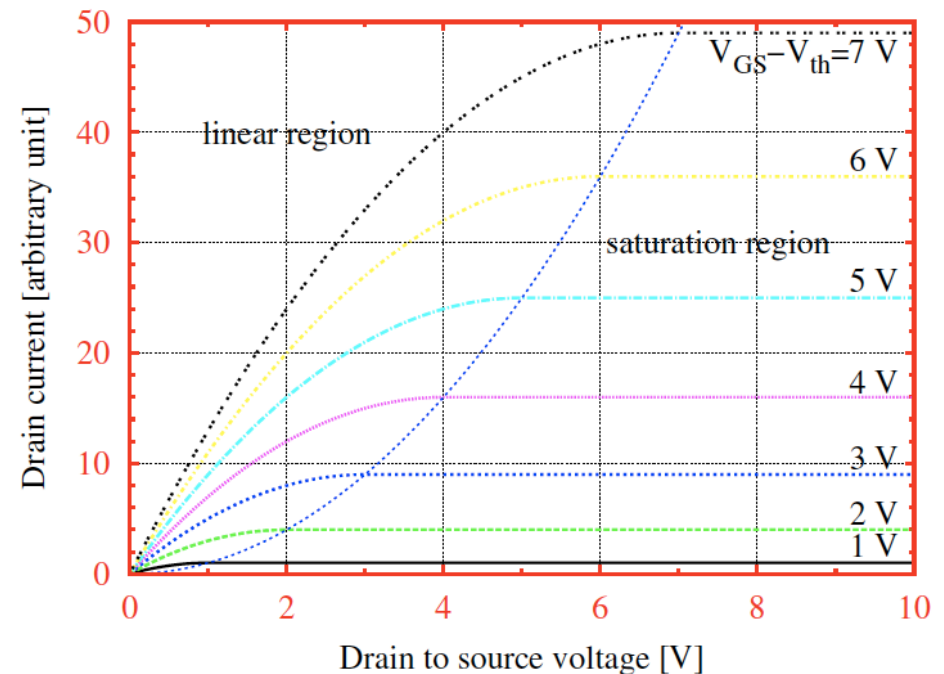
- ❑ Identify Region
- ❑ Understand governing equations
- ❑ Use region and equations to understand operation





Big Idea

- ❑ Semiconductor can act like metal or insulator
- ❑ Use electric field to modulate conduction state of semiconductor
- ❑ 3 Regions of operation for MOSFET
 - Linear
 - Saturation
 - With channel length modulation
 - Subthreshold





Admin

- ❑ HW 2 due 2/9 (Friday)
 - Make sure you label plots with node names (label nodes with relevant names, not just net0)
 - Reminder: OH every day of the week

- ❑ More Fabrication Videos:
 - From sand to silicon (intel) -
<https://www.youtube.com/watch?v=Q5paWn7bFg4>
 - How microchips are made -
<https://www.youtube.com/watch?v=F2KcZGwntgg>



Acknowledgement

- ❑ Prof. André DeHon (University of Pennsylvania)
- ❑ Prof. Jing Li (University of Pennsylvania)